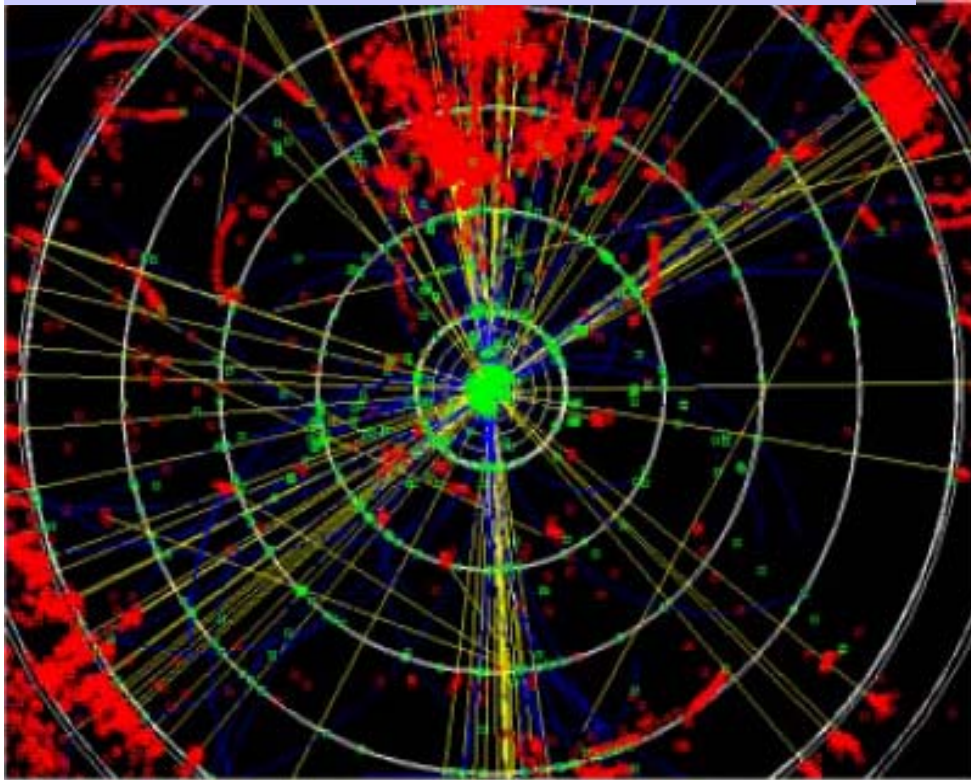
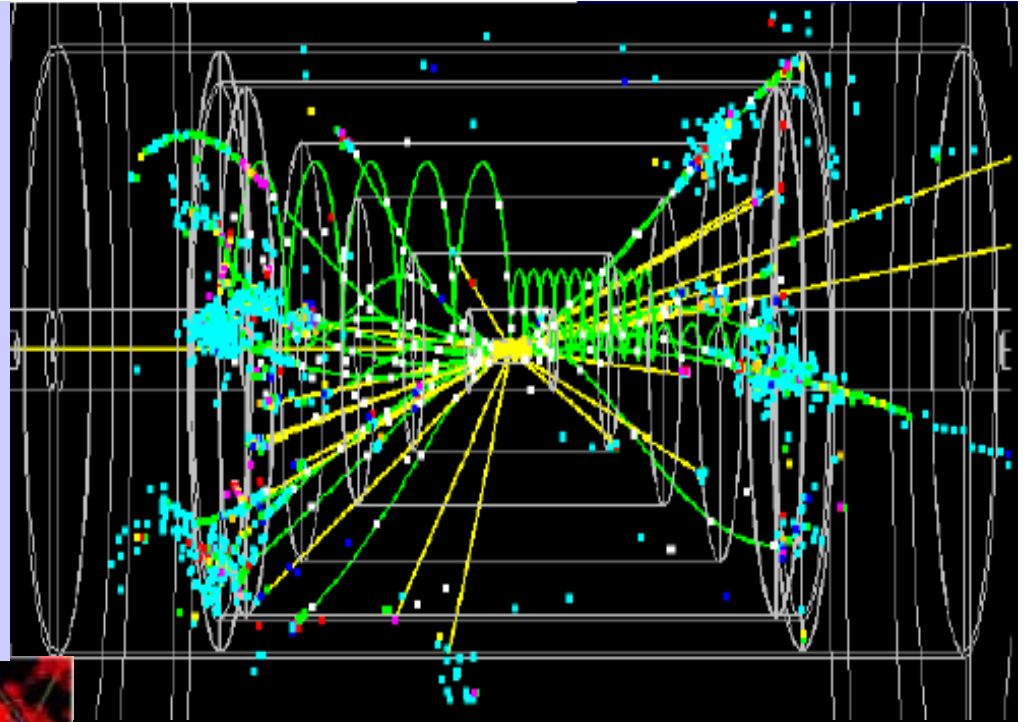
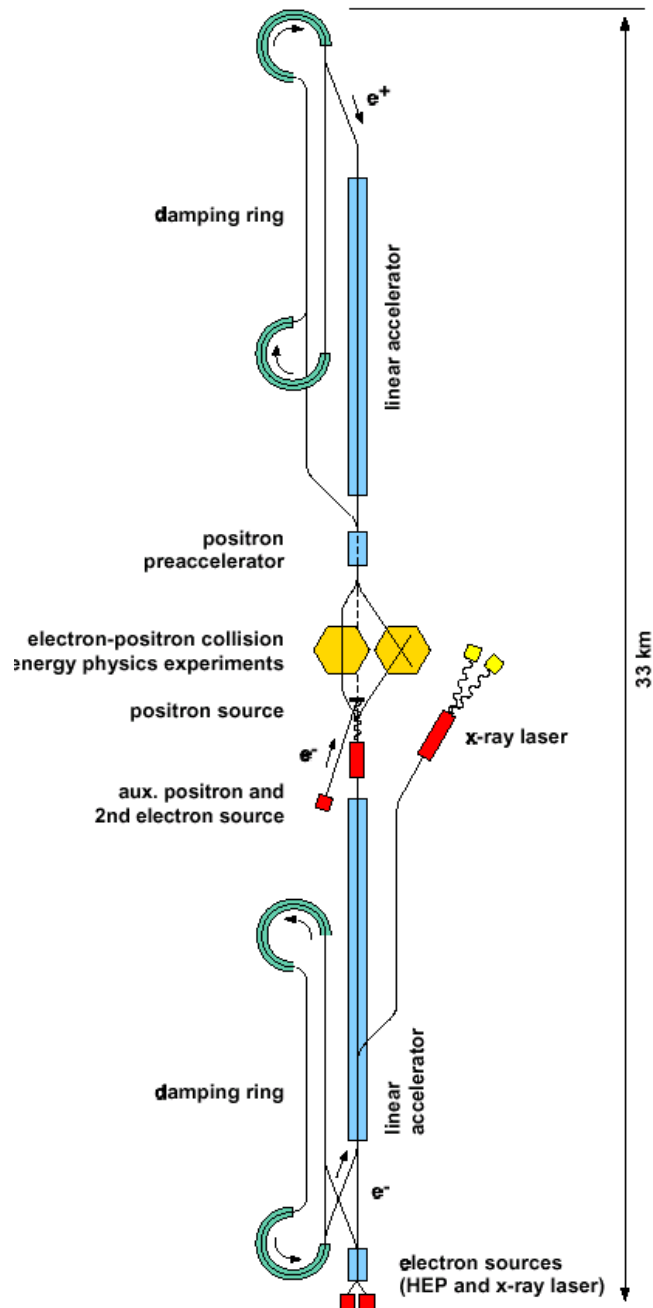


R&D on Front-End Electronics for Linear Collider Detector Applications



Bruce Schumm
LECC2004 Workshop
Boston, Mass.
September 13, 2004



Principle 1:

The Linear Collider is not the LHC.

$$E_{cm}^{LHC} = 14 \text{ TeV} \quad E_{cm}^{LC} \approx 0.5 \text{ TeV}$$

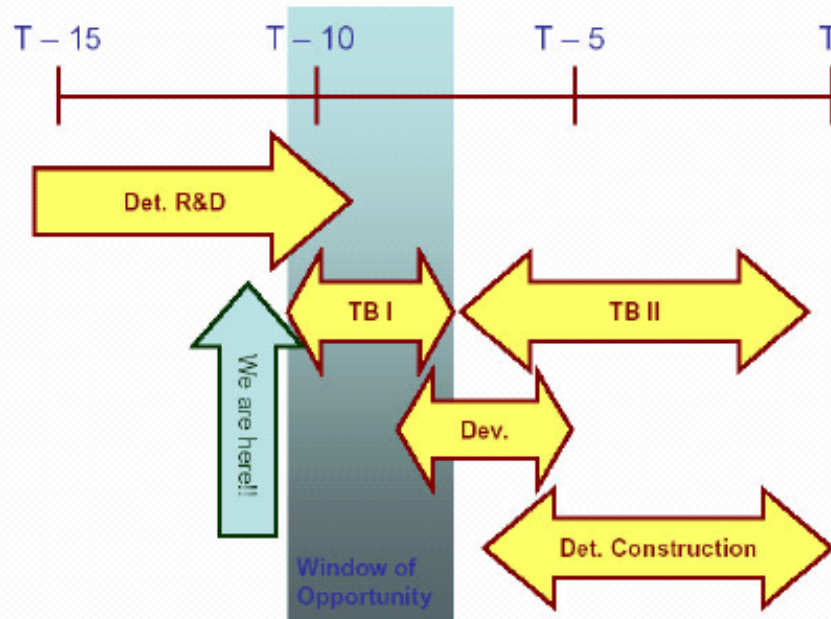
What the LC lacks in brute-force discovery reach, it must make up with finesse → the LC requires a precision detector, and the electronics to instrument it.

To understand the need for R&D on front-end electronics for the Linear Collider, it is essential to consider the physics one wants to do.

By the way... the time frame for this R&D
is surprisingly current

Jae Yu, UT Arlington

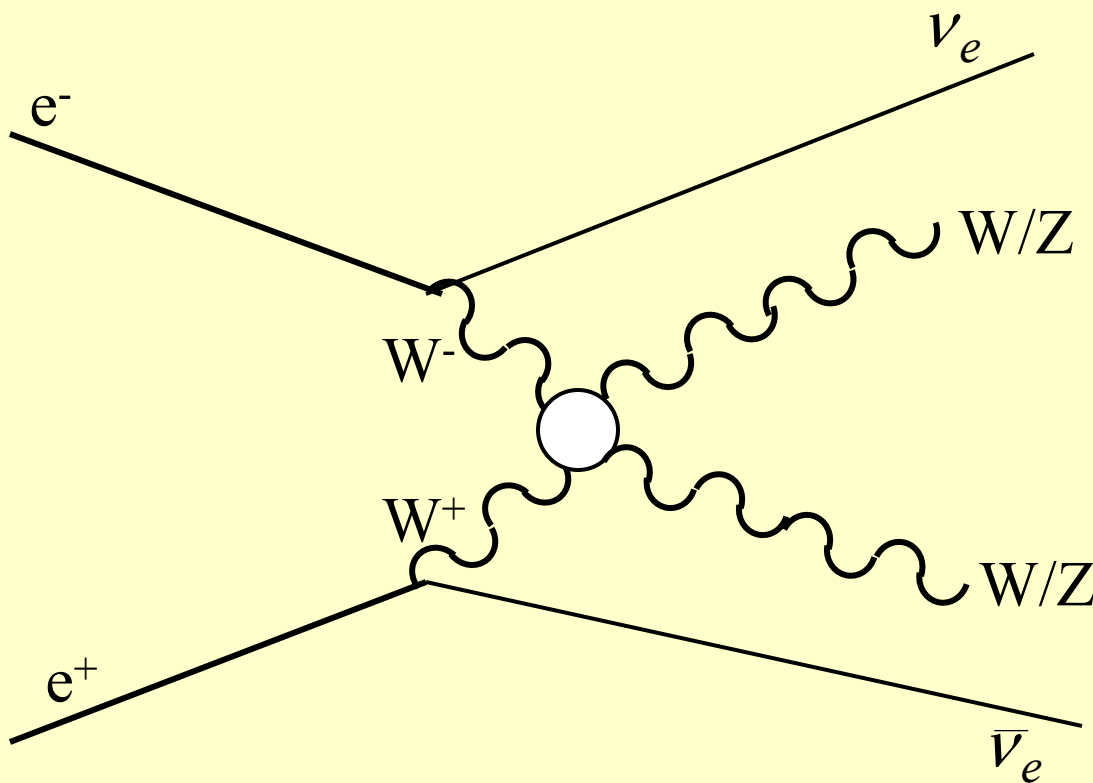
LC Detector Time Scale



Time	T=2015	Tasks
T - >10~11	Before 2005	Detector R&D
T - 10~11	2005~6	Test Beam I
T - 8~9	2006~7	•Detector Technology chosen. •Detector Development and design begins
T - 6	2009	Detector Construction begins Test Beam II (Calibration)
T	2015	LC and Detector ready

Linear Collider Physics

Given what we have discovered so far, for high enough energy, this process will happen with greater than unit probability. → Our current understanding is incomplete!

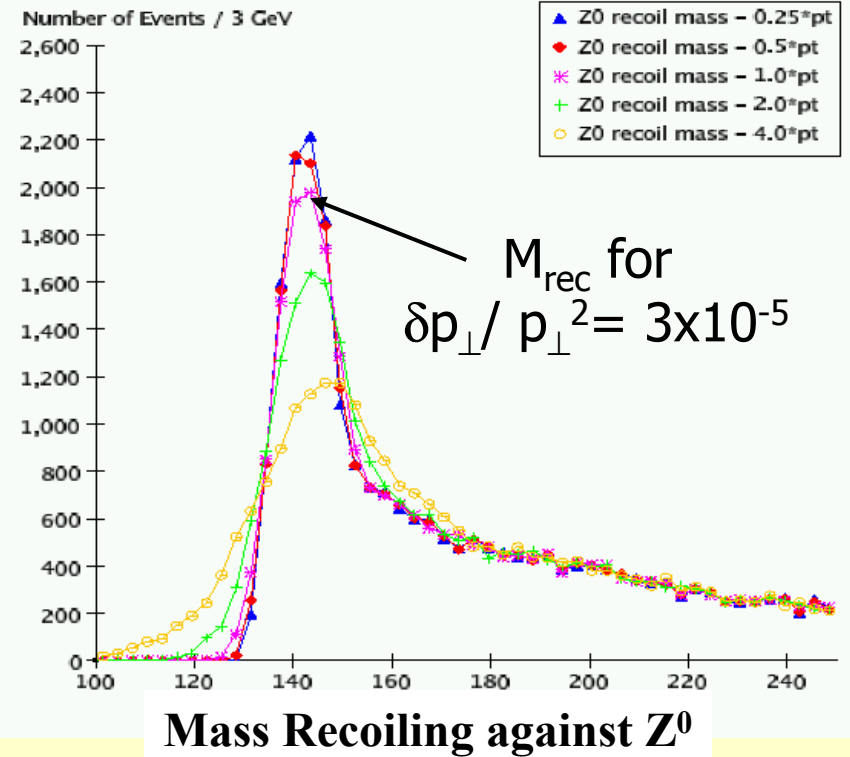


We need something new to put in the circle.
Here are some thoughts...

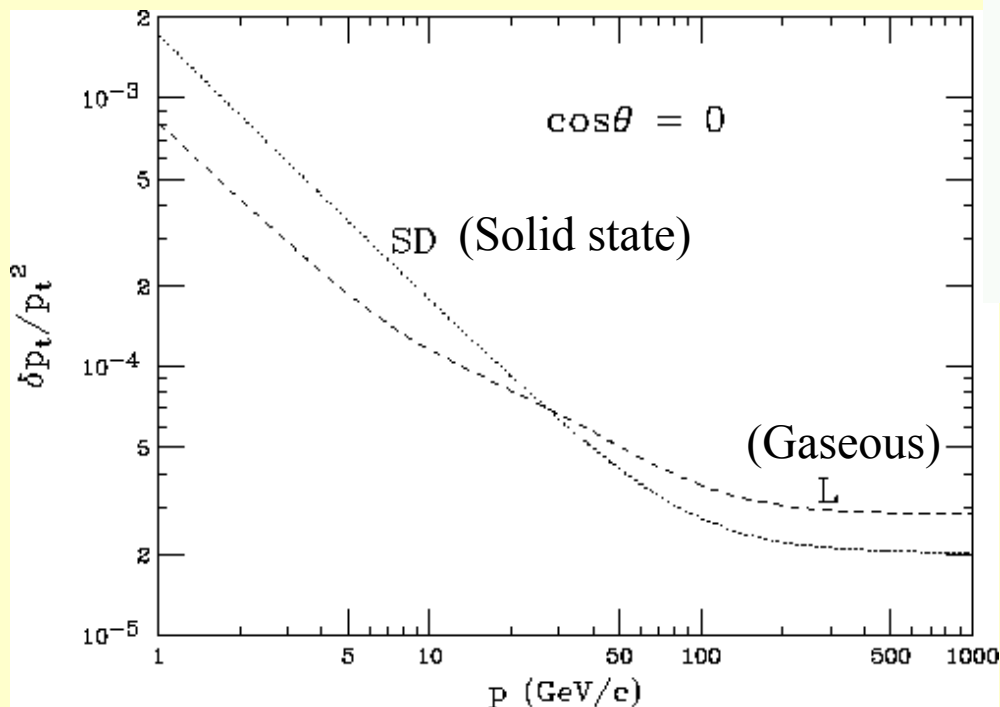
THE HIGGS (h^0)

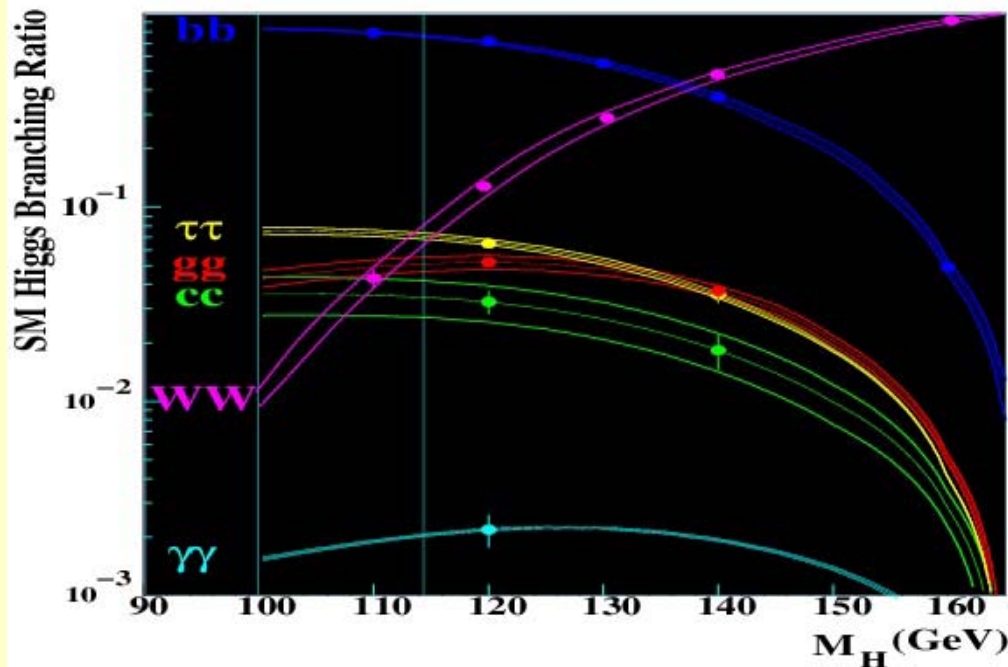
Haijun Yang, Michigan

LC Physics
demands
precise
tracking



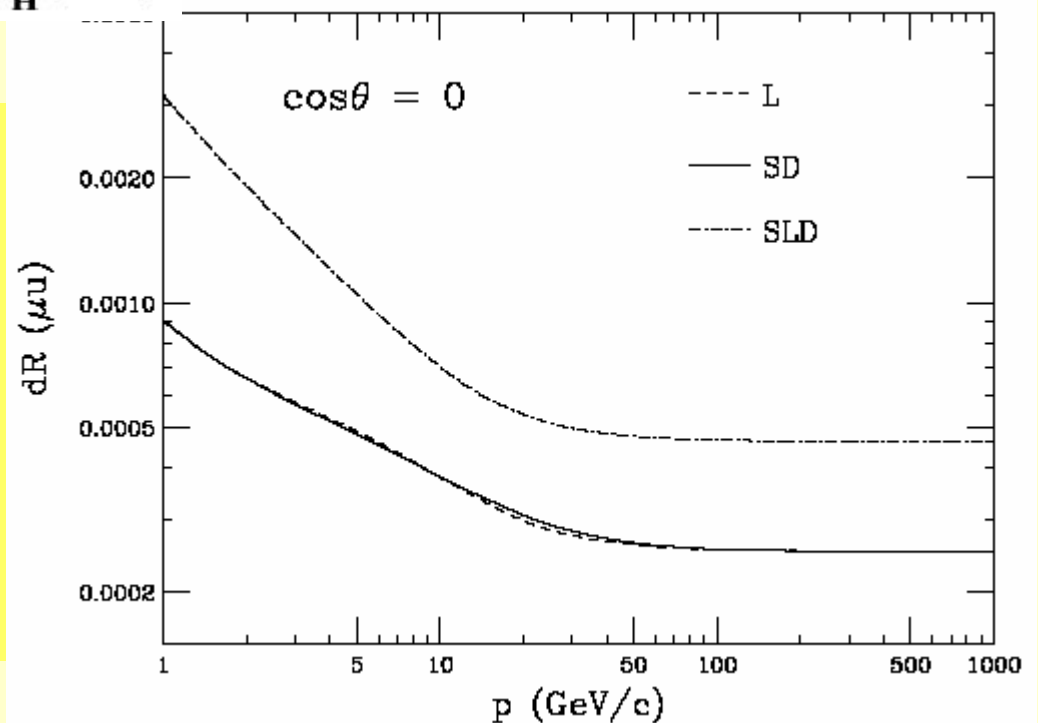
Precision demands
state-of-the-art central
tracker resolution

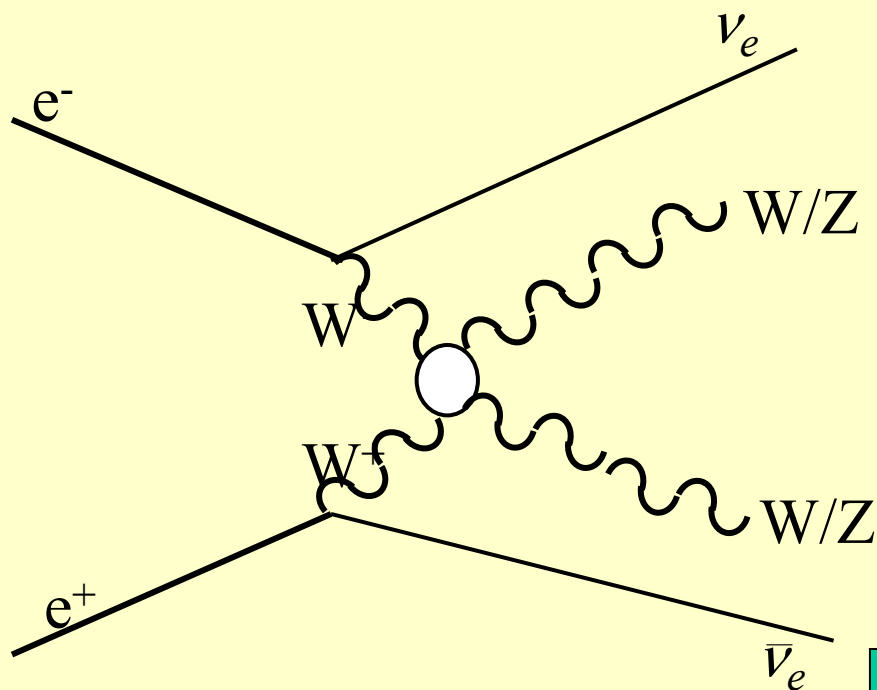




The LC must do more than just confirm LHC's Higgs discovery. It must probe Higgs properties with the precision needed to detect subtle new physics scenarios (SUSY, Little Higgs, etc.)

Model-independent branching fractions require unprecedented bottom and charm tagging
 → ultraprecise three-dimensional vertexing

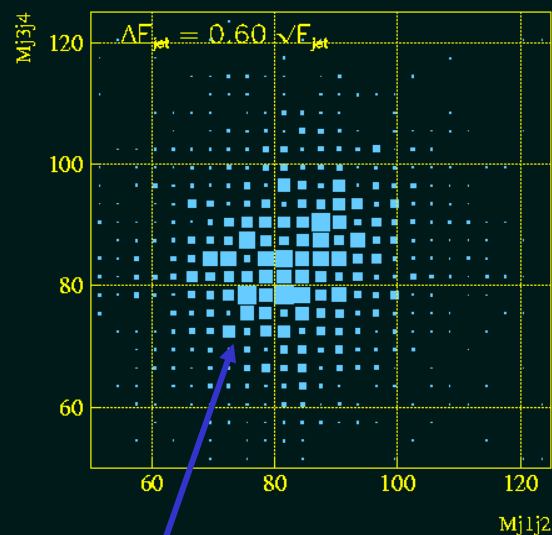




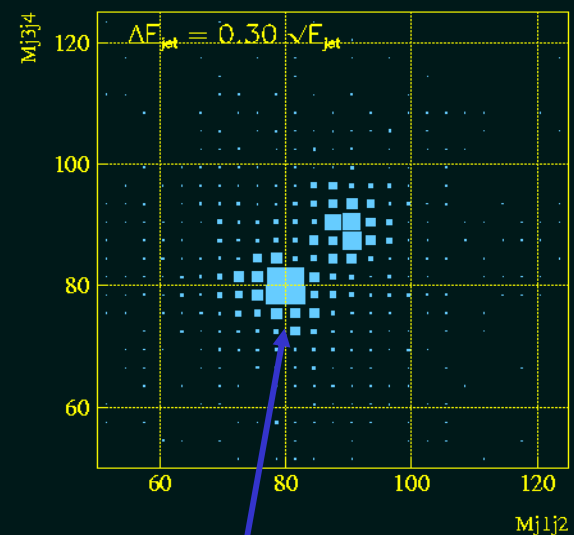
If Higgs is just a fairy tale,
then more exotic states must
play a role \rightarrow ‘Strong WW
Scattering’

Henri Videau; Ecole Polytechnique

Essential final-state
discrimination must
be done calorimet-
rically \rightarrow ‘Energy-
flow reconstruction’
places demands on
calorimeter design



$$\Delta E_{jet} = 0.60 \sqrt{E_{jet}}$$

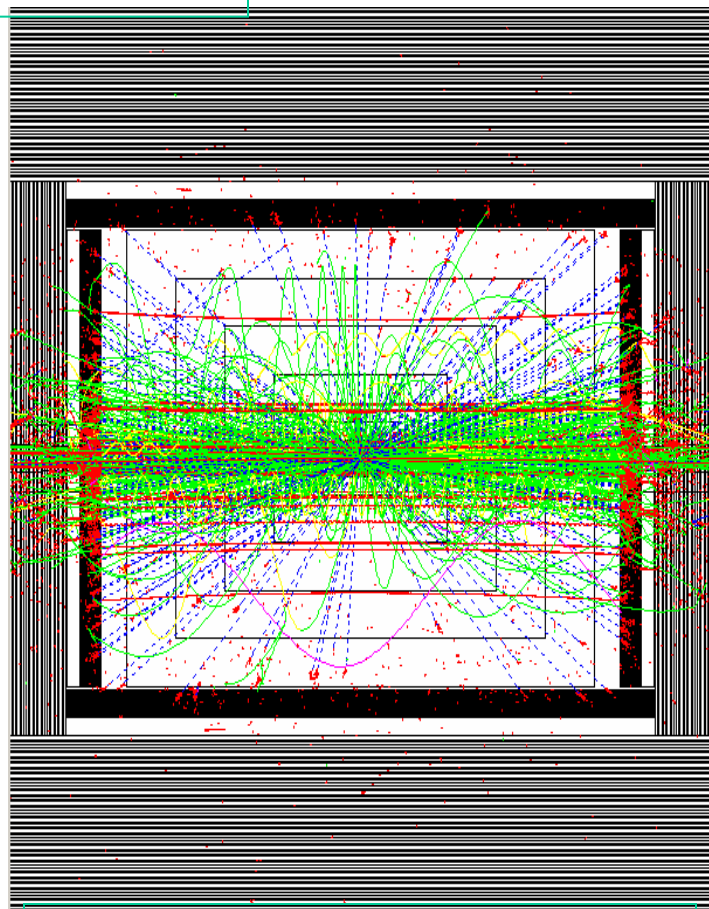


$$\Delta E_{jet} = 0.30 \sqrt{E_{jet}}$$

Timing is Important

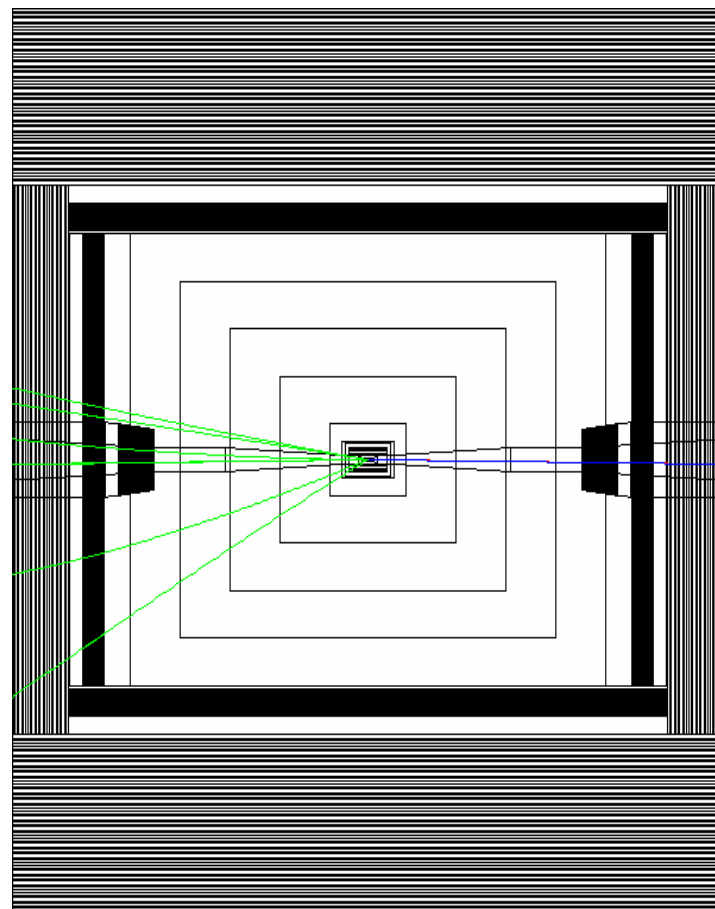
Pileup of $\gamma\gamma \rightarrow$ hadrons for ~ 200 beam crossings

T. Barklow



Pileup from 192 crossings
(56 Hadronic Events)

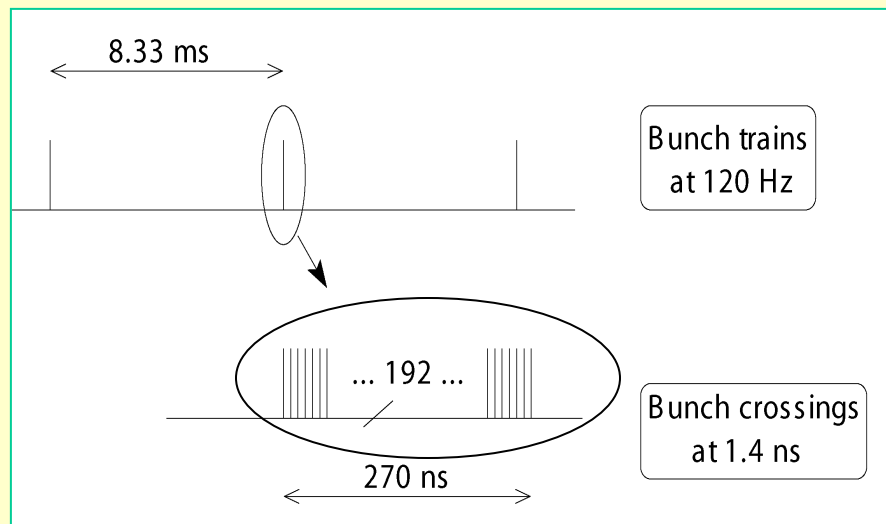
Timing in Cal
and Tracking
→
Systems
needs to be
considered



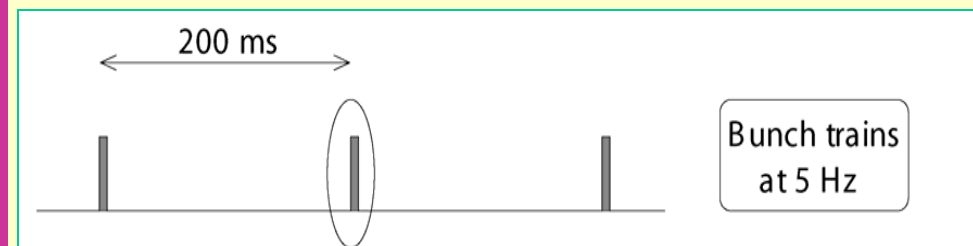
Pileup from 3 crossings

So... what do we mean by 'timing'?

The Technology Choice



WARM: Short, intense spill (192 pulses separated by 1.4 ns), and often (120 Hz)



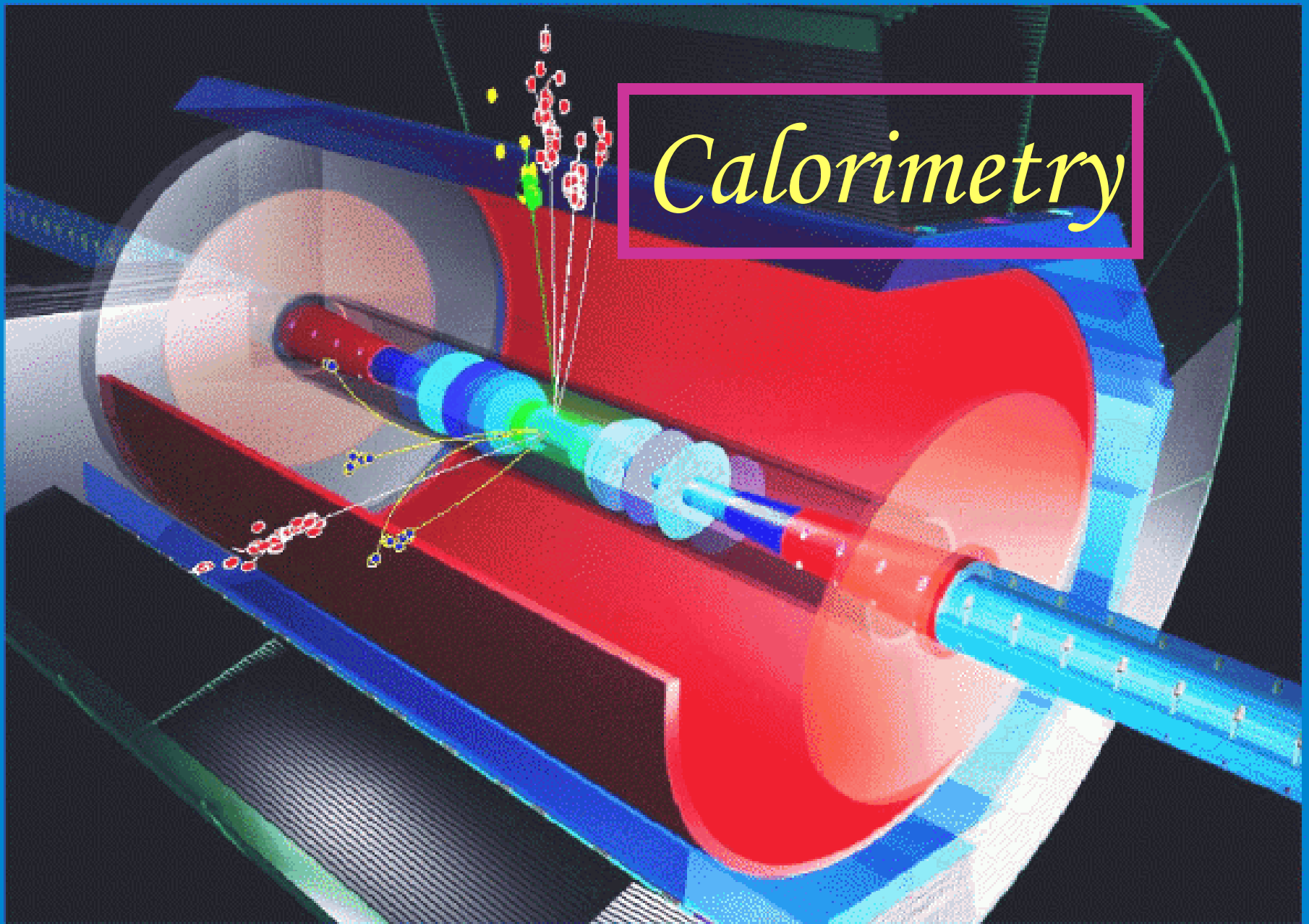
**Duty Cycle:
 5×10^{-3}**

COLD: Relaxed but persistent spill (2820 pulses separated by 337 ns); occasional (5 Hz)

And the choice is...

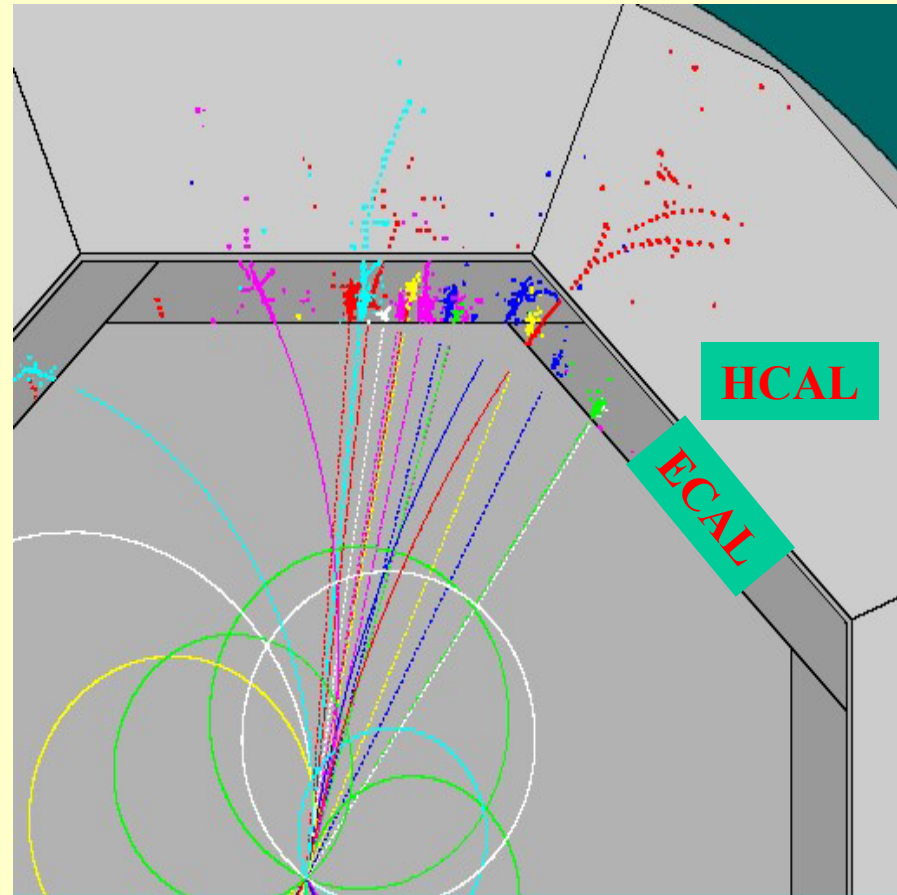
COLD

Calorimetry

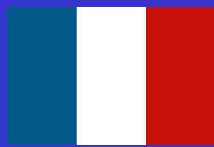
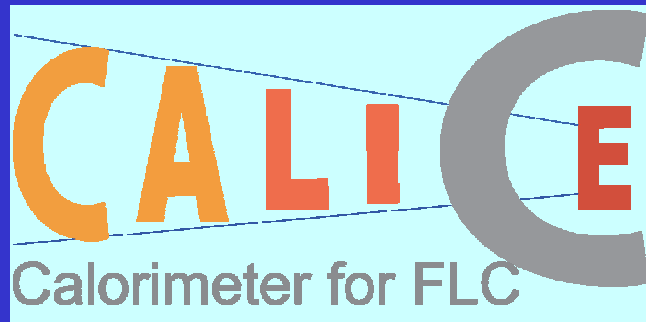


The Energy-Flow Concept

- Photons and high-energy electrons measured best with calorimetry (ECAL)
 - Charged hadrons measured best in tracker
- ➔ Separate clusters in calorimeter and decide what to hand back to tracker



Requires 'tracking calorimeter' with minimal shower spread and maximal segmentation (Moliere radius of W is about 1 cm)



CALICE is a consortium
of 28 institutions from 8
nations

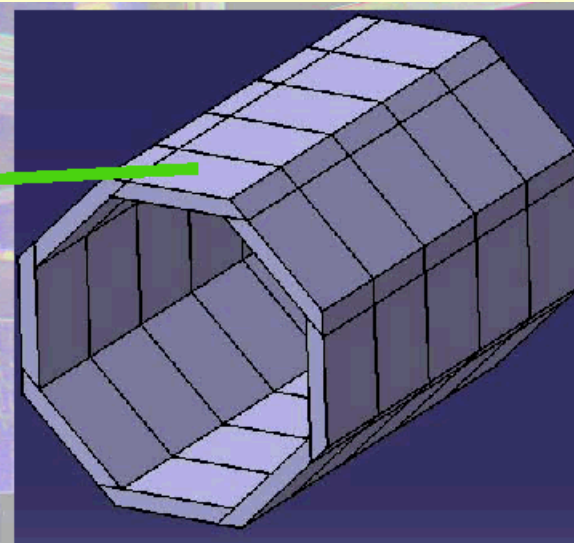
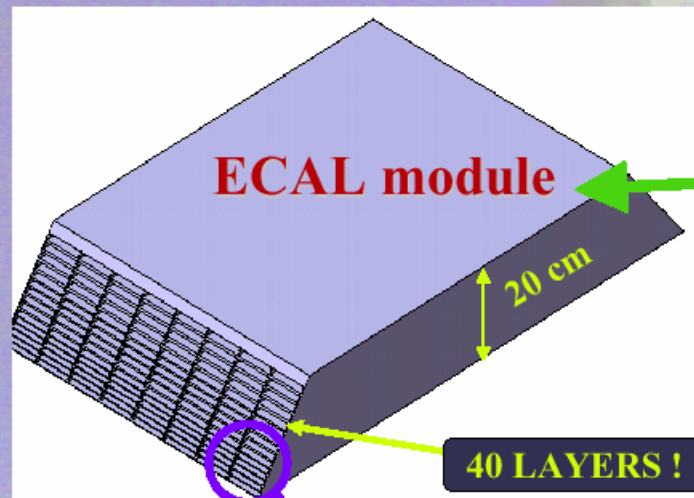
The SD Si/W Group

M. Breidenbach, D. Freytag,
N. Graf, G. Haller, O.
Milgrome

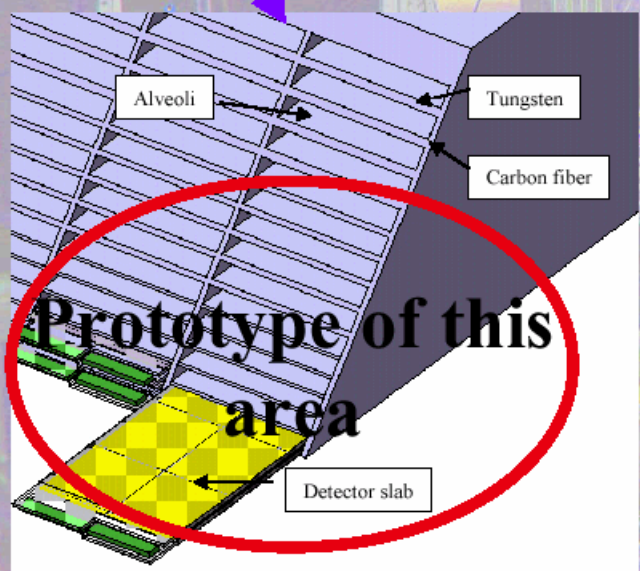
*Stanford Linear Accelerator
Center*

R. Frey, D. Strom
U. Oregon

V. Radeka
Brookhaven National Lab



(TESLA
TDR)



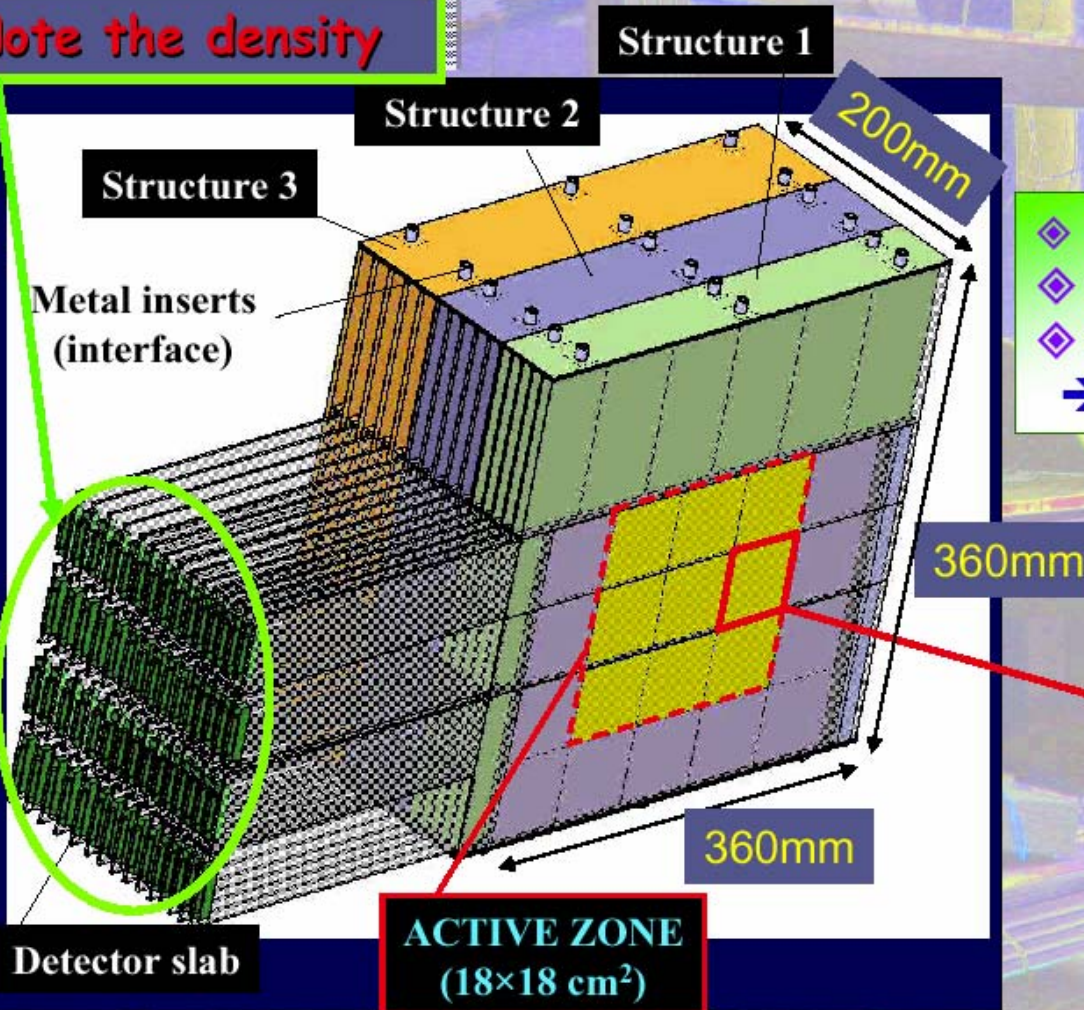
Proposal for ECAL:

- Thin Si diodes read out showers in W layers (Si/W)
- Read out *each layer* with granularity given by $R_{\text{molier}} (1 \text{ cm}^2)$

Challenge: This implies a few $\times 10^7$ channels

The ECAL prototype

Note the density



CALICE ECAL



LAL,LLR,LPC,PICM



Imperial College, UCL, Cambridge,
Birmingham, Manchester, RAL



ITEP,IHEP,MSU



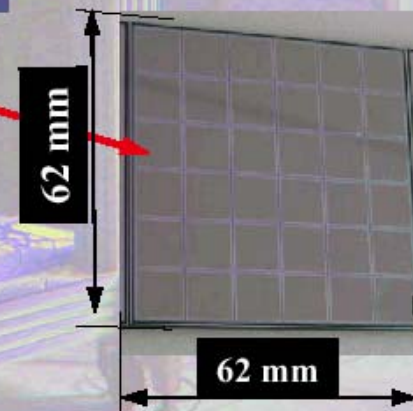
Prague (IOP-ASCR)



SNU,KNU

- ◆ 3 structures W-CFi (1,2,3 x1.4mm)
 - ◆ 15 « detector slabs »
 - ◆ Dimension 200x360x360 mm
- ➔ 9720 channels in prototype

Silicon wafers with
6x6 pads (10x10 mm²)



Presentation of the front-end electronic (J. Fleury, LAL Orsay)

6 active wafers

Made of 36 silicon PIN diodes

→ 216 channels per board

Each diode is a 1cm^2 square

2 calibration switches chips

6 calibration channels per chip

18 diodes per calibration channel

12 FLC PHY3 front-end chip

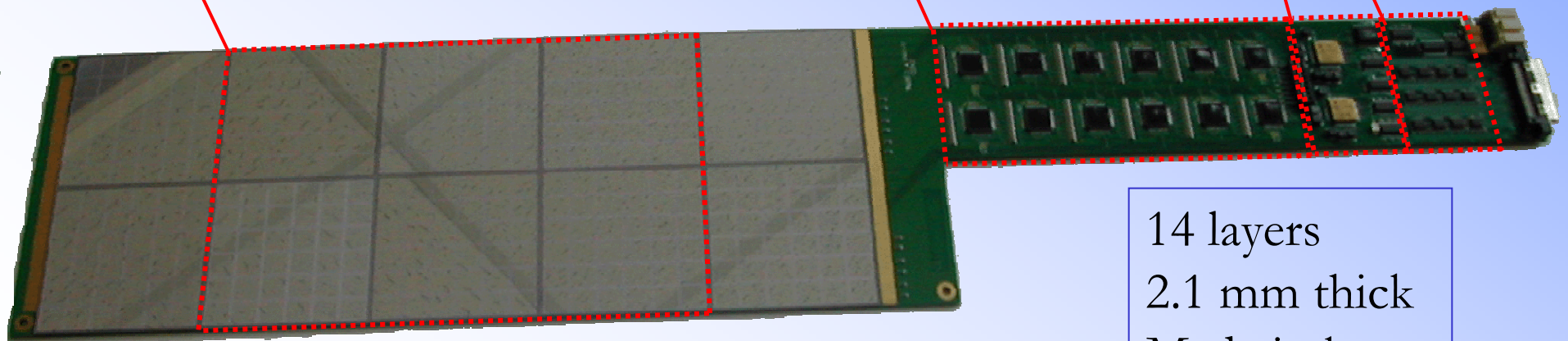
18 channels per chip

13 bit dynamic range

Line buffers

To DAQ part

Differential



14 layers

2.1 mm thick

Made in korea

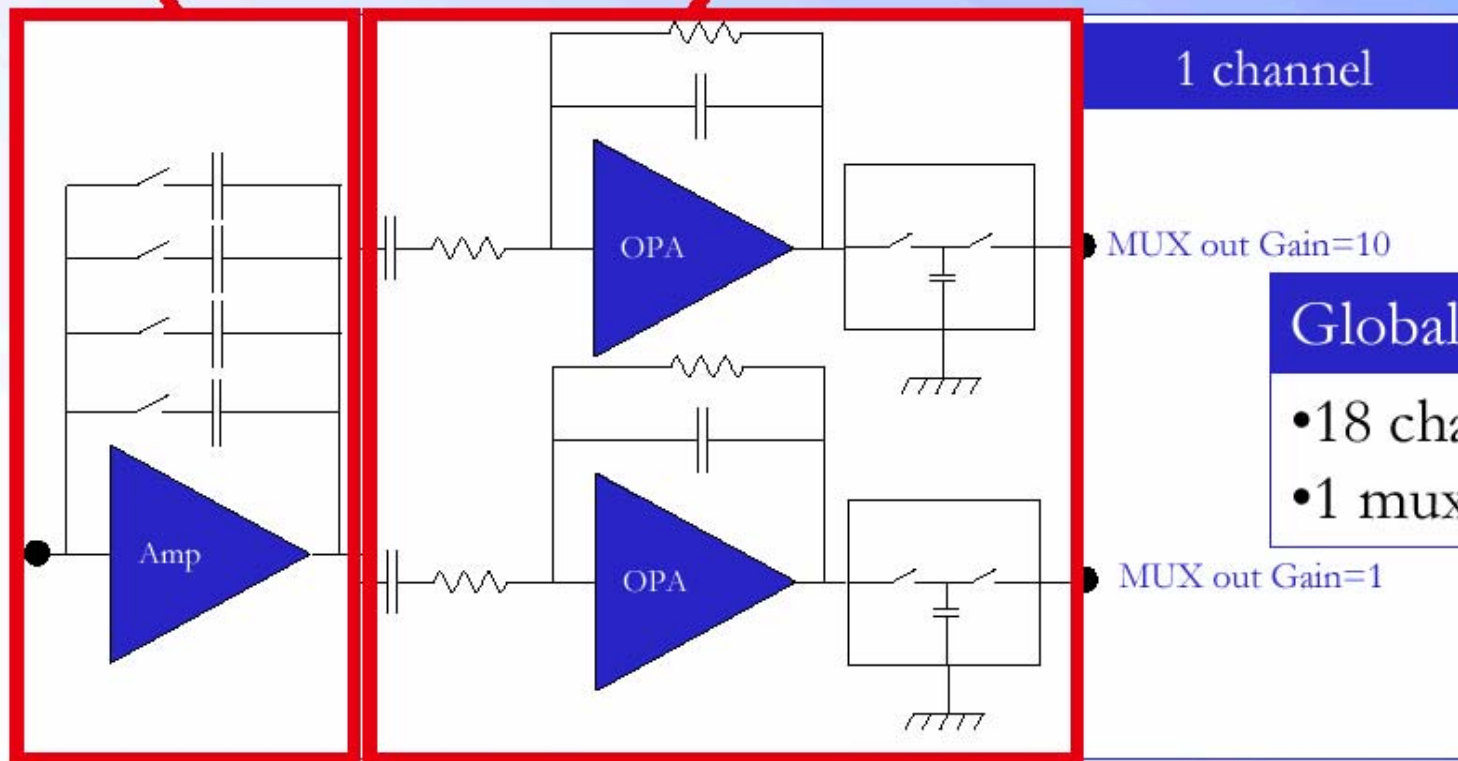
Multi-gain charge preamp

- 4 bits for gain selection
- Gain from 0.3 to 5 V/pC
- Gain selected offline

Dual shaper & track and hold

- Gain 1 and gain 10
- Work in parallel to select gain *a posteriori*

Process: 0.8 μm BiCMOS



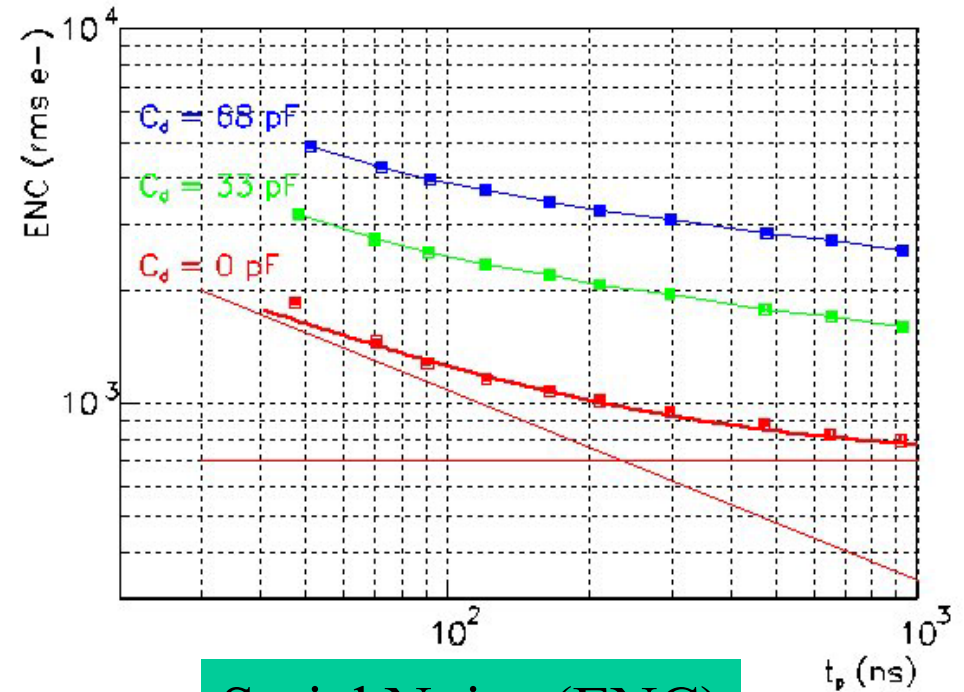
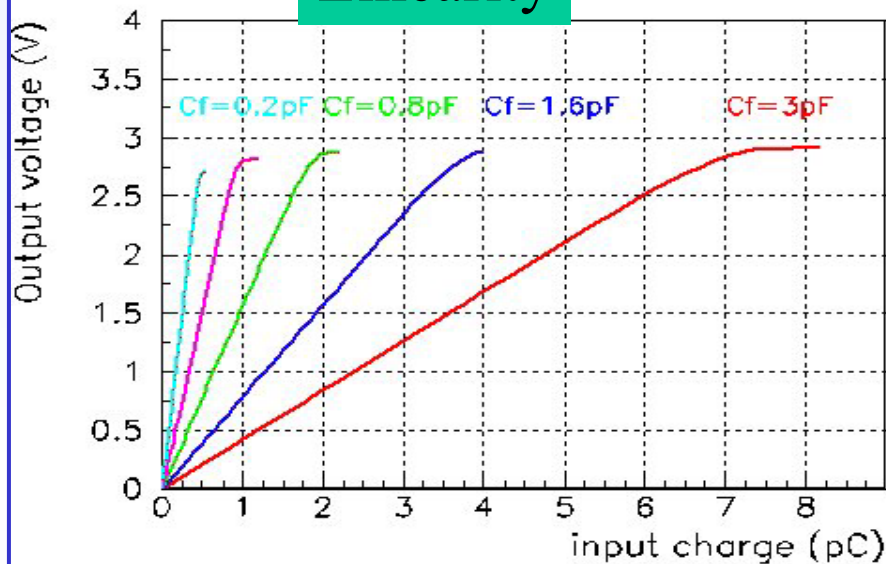
Global characteristics

- 18 channel input
- 1 mux output

FLC-PHY3 Chip (LAL Orsay)

Based on blocks
from OPERA HPD
readout ASIC

Linearity



Serial Noise (ENC)

At $\tau \sim 200$ nsec, C_{det} in pF:

$$ENC = 1720 + 28 * C_{det} \text{ (x1 gain)}$$

$$ENC = 950 + 34 * C_{det} \text{ (x10 gain)}$$

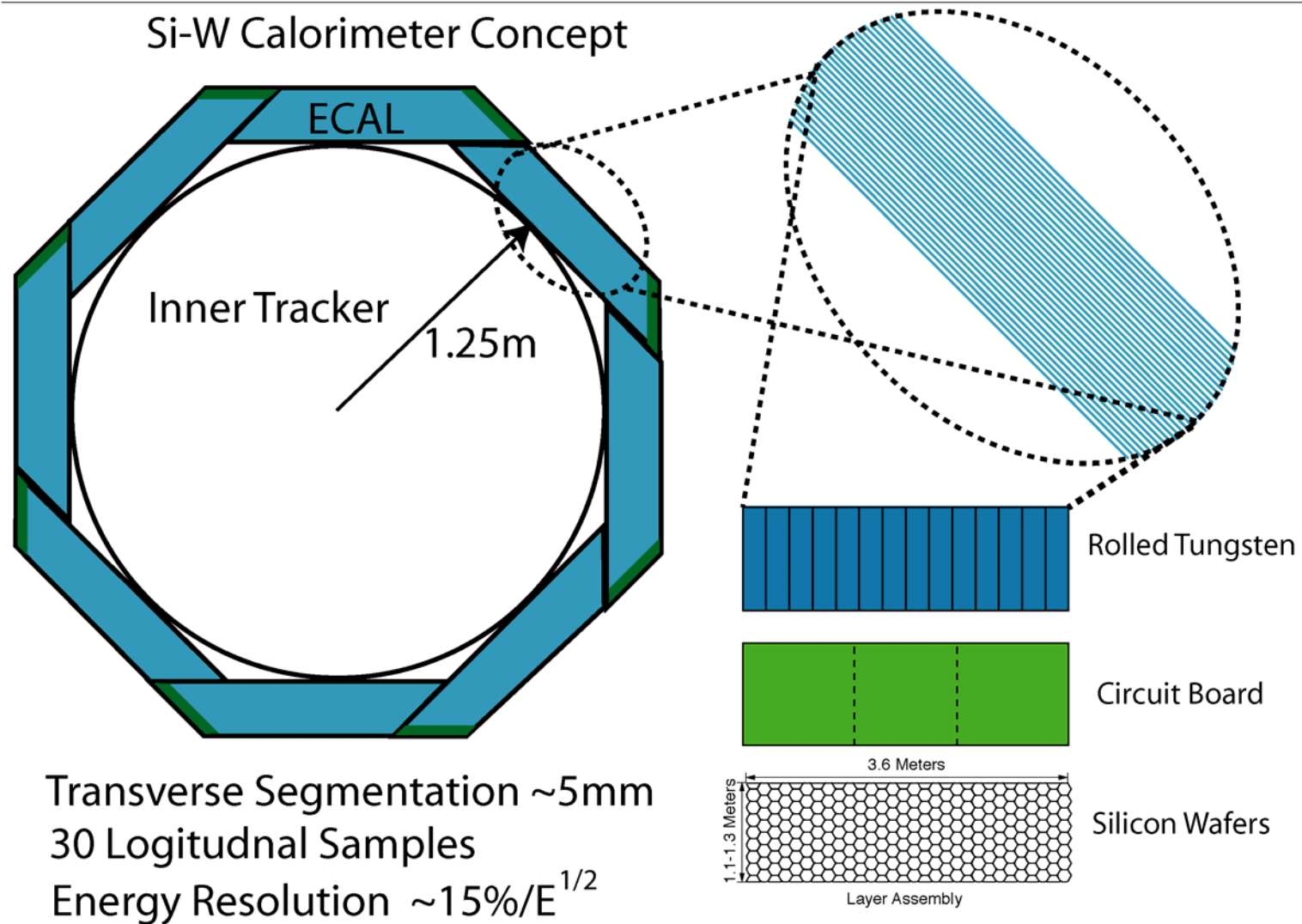
Now available for instru-
mentation of CALICE ECAL
prototype (~2000 packages)

Threads in ongoing ECAL front-end electronics Research and Development

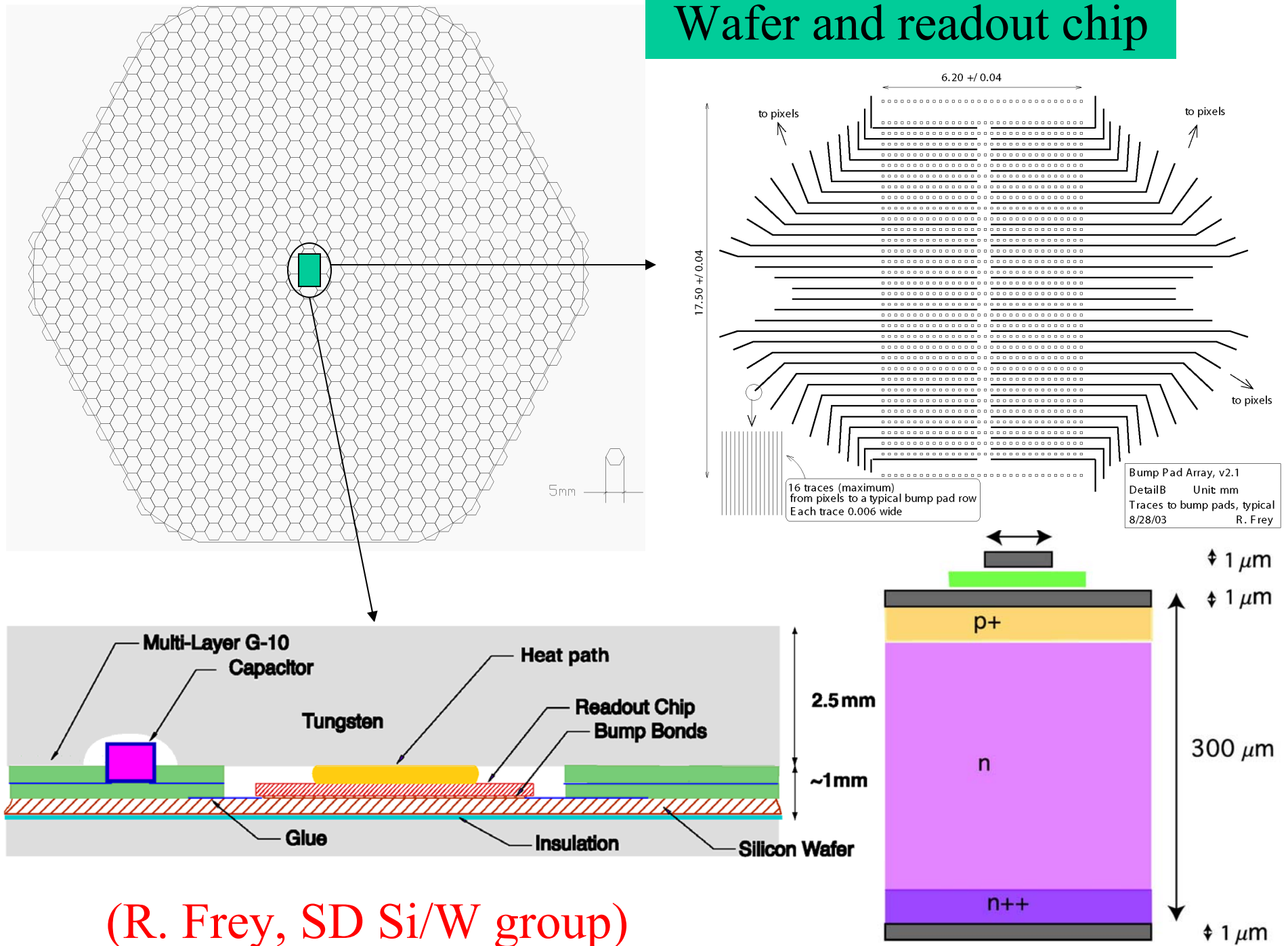
For precision calorimetry, compactness is important

- Maintain Moliere radius
 - Calorimetry inside coil
 - Handle staggering channel count
-
- ➔ Multi-channel electronics integrated into detector volume
 - ➔ Power cycling to avoid active cooling
 - ➔ Zero-suppression, timing to avoid pile-up

SD Si/W Ecal Concept (R. Frey, SD Si/W group)



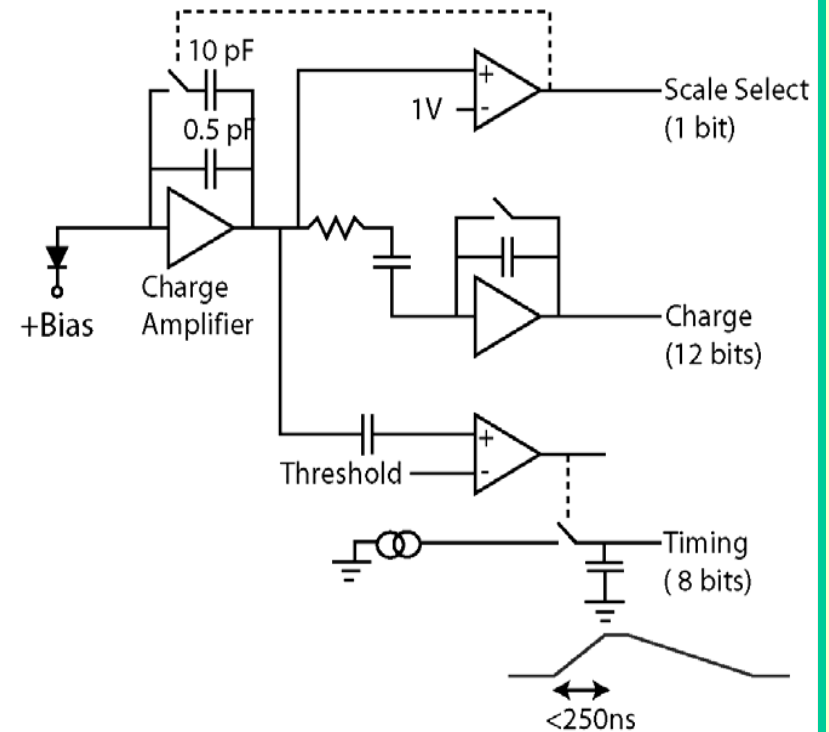
Wafer and readout chip



(R. Frey, SD Si/W group)

SD Si/W ASIC

- Capacitance
 - Pixels: 5.7 pF
 - Traces and pre-amp: 22 pF
- Resistance
 - 300 ohm max
- Power
 - < 40 mW/wafer \Rightarrow power cycling
(An important LC feature!)
- Signal Processing
 - Provide fully digitized, zero suppressed outputs of Q and T
 - One ASIC per wafer
- Signals
 - < 2000 e noise
 - Require MIPs with $S/N > 7$
 - Max. signal 2500 MIPs (5mm pixels)



Dynamically switched C_f

- Signals after 1st stage larger
 - ~ 0.1 mV \rightarrow 6.4 mV for MIP
- Much reduced power
 - Large currents in 1st stage only

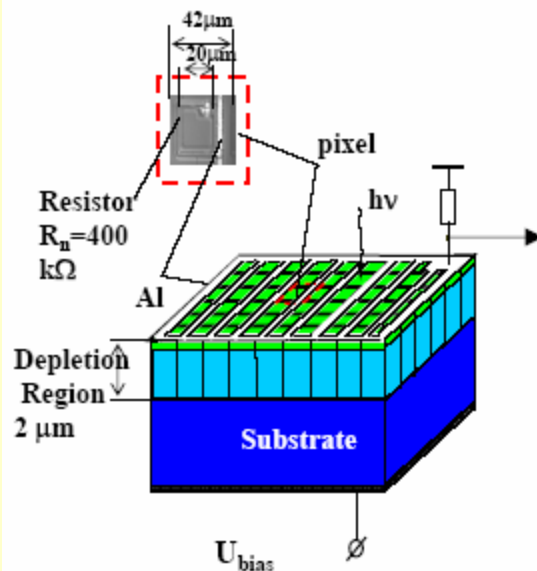
CALICE will pursue similar development

Hadronic Calorimeter (HCAL)

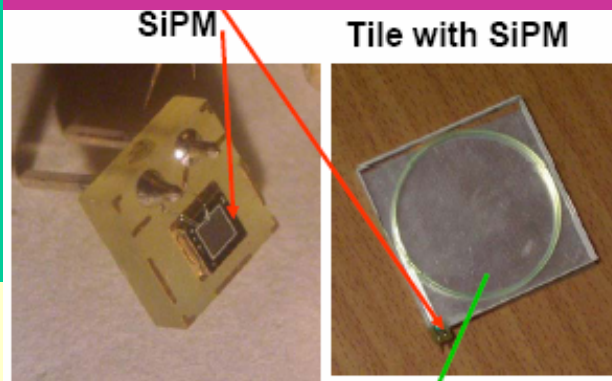
Need to maintain longitudinal and transverse segmentation:

- $5 \times 5 \text{ cm}^2 \rightarrow$ 'Analog HCAL'
- $3 \times 3 \text{ cm}^2 \rightarrow$ 'Semi-digital HCAL'
- $1 \times 1 \text{ cm}^2 \rightarrow$ 'Digital HCAL'

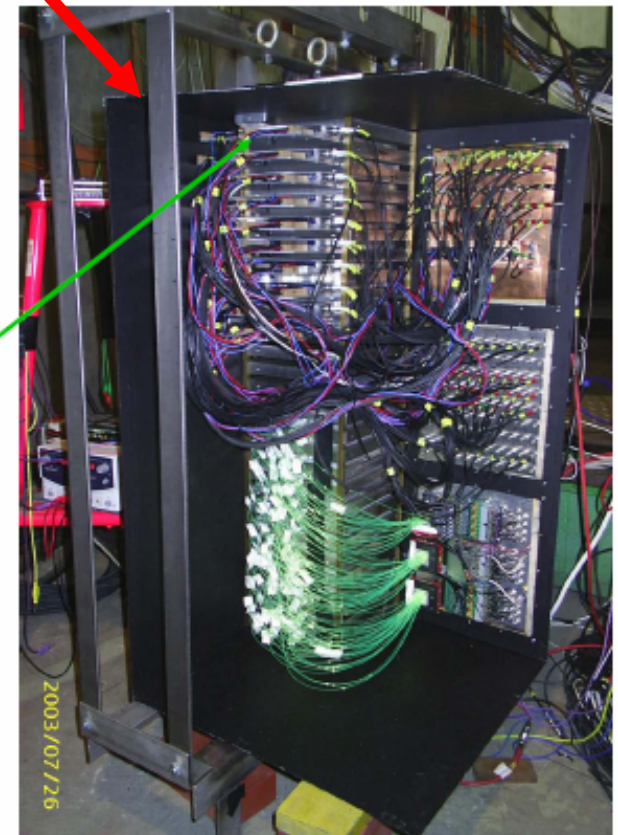
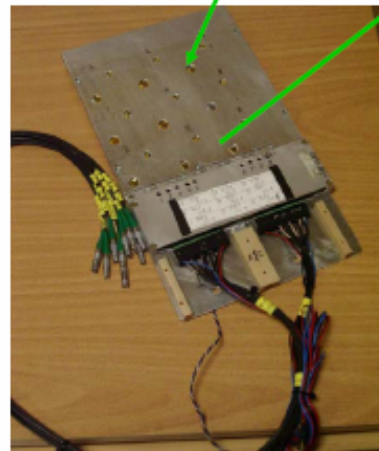
Silicon Photomultiplier (SiPM)
Ganged Geiger-mode pixels



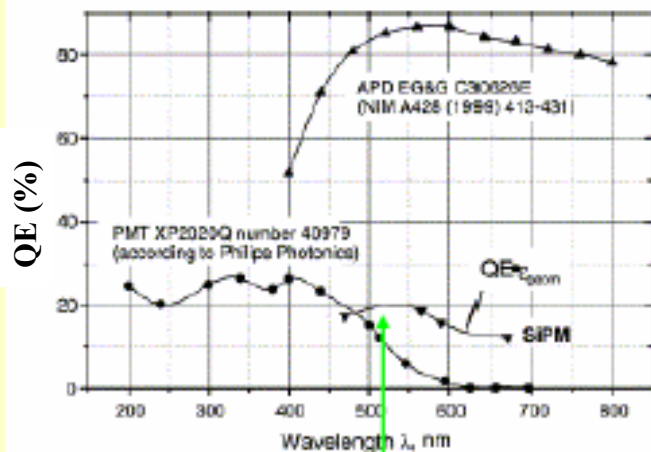
Moscow Engineering and Physics Institute



cassette
3x3 tiles



SiPM Electronics Development



WLS fiber emission

Quantum Efficiency similar to PMT, but single-stage gain, so better statistically than PMT or APD (single-PE statistics)

SiPM signals:

gain 10^6 : 1 photo electron = 160 fC
MIPs ~ 25 p.e. = 4 pC
dyn range: Max signal = 400 pC
fast: few ns rise time
pulse shape set by wavelength shifter fiber

SiPM noise:

2MHz noise rate (signal every 500ns)
dominated by 1 pixel signals
necessary calibration signal
But could pile up with slow shaping

SiPM calibration

Felix Sefkow, DESY

- The **MIP** signal determines the **energy scale**

- monitor overall response

- scint, SiPM, FEE

- **LED**: inject UV into scintillator:

- **Single photon peak spacing** *a must!*

- **non-linearity correction**
(together with MIP and universal response function)

- **gain monitoring:**

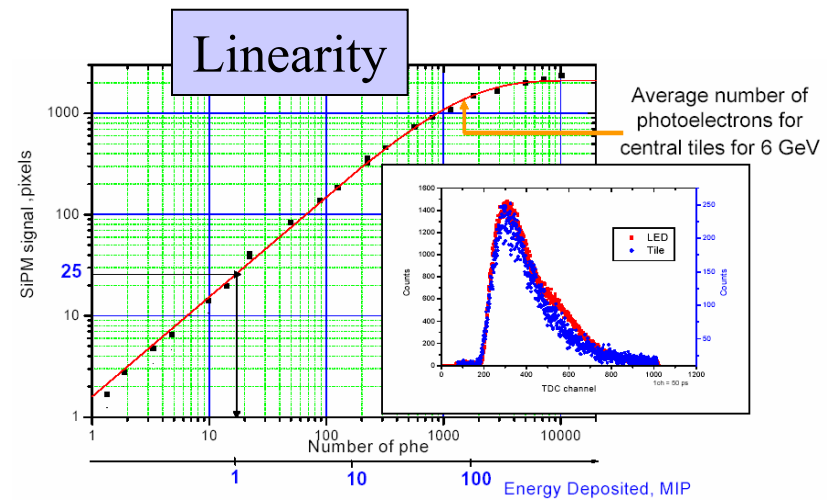
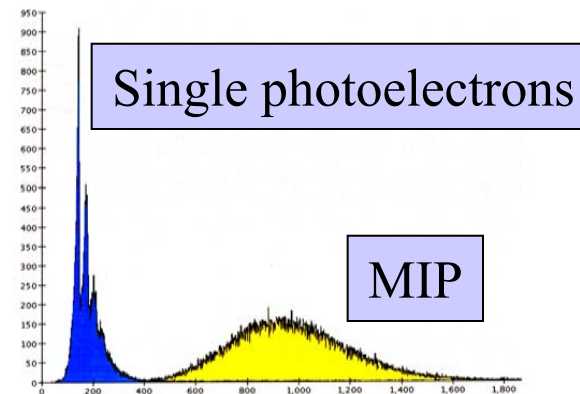
SiPM temperature sensitivity:

Gain: 3%/K, Signal: 4%/K

- **Medium LED signals: stability**
between MIP calibration runs
- **Large LED signals: direct non-linearity** monitoring

- Charge injection: electronics calibration

Picture from PC screen: LED and electron spectra



Two Shaping-Time/Two Gain Solution

Calibration mode (short shaping)

Single photoelectron response

$C_f = 0.2 \text{ pF}$; $\tau = 12 \text{ ns}$

1 spe = 8.9 mV ; $t_p = 40 \text{ ns}$

Noise : 720 μV rms

Physics mode (longer shaping)

MIP (=16pe) response

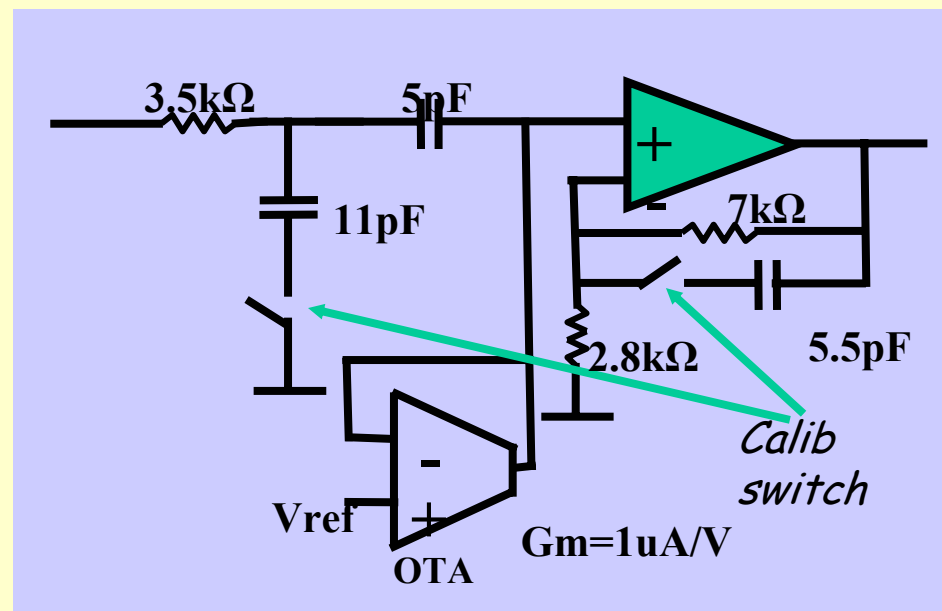
$C_f = 0.4 \text{ pF}$; $R_c = 5 \text{ k}$; $\tau = 120 \text{ ns}$

Gain = 12 mV/MIP ; $t_p = 186 \text{ ns}$

Noise = 570 μV rms

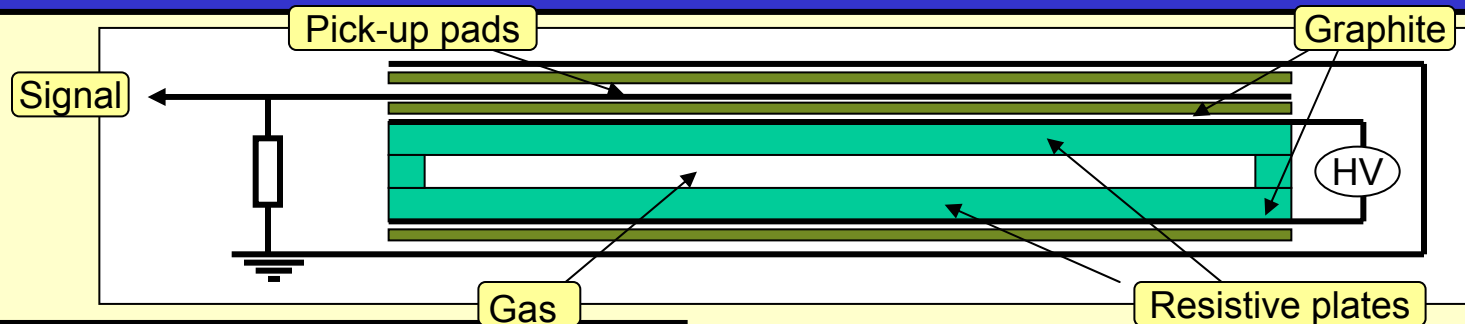
Unipolar/Two Gain Solution

(avoid overshoot that can lead to single PE pile-up)



Both on same prototype ASIC; to be submitted

ASIC for 'Digital HCAL' – 1 cm² RPC's



American Linear Collider
Physics Group

Conceptual Design
of the
Amplifier/Discriminator/Timestamp (ADT) ASIC

Gary Drake, José Repond, Dave Underwood, Lei Xia
Argonne National Laboratory

Charlie Nelson
Fermilab

Version 1.20
February 23, 2004

64 inputs with choice of
input gains

RPCs (streamer and
avalanche), GEMs...

Triggerless or triggered
operation

Output: hit pattern and
time stamp

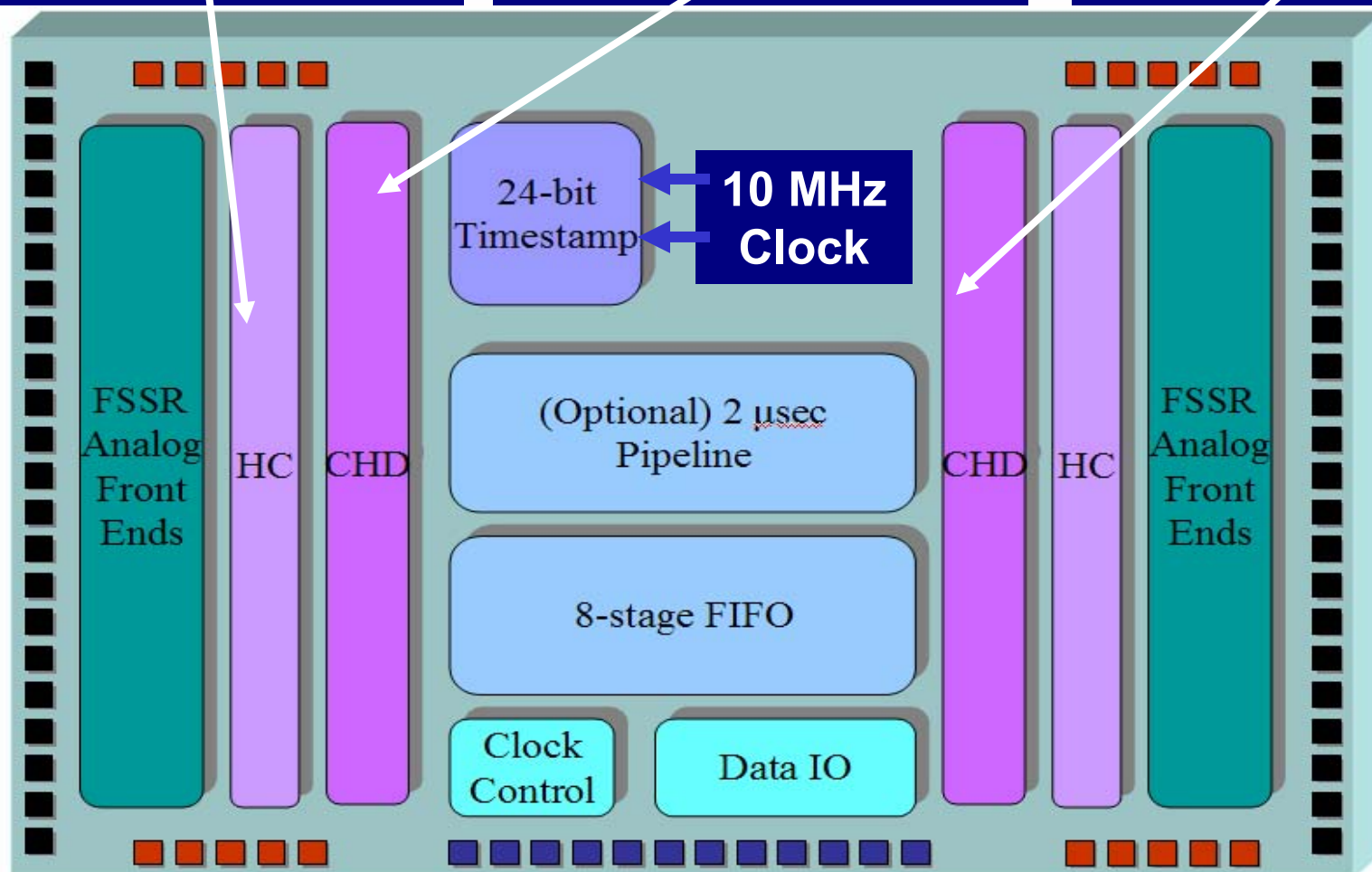
J. Repond, Argonne

Digital HCal ASIC

Analog circuitry taken from recently built FSSR chip (BTeV)

Hit catcher with possibility to mask noisy channels

Chip has data indicator (essentially a fast OR)



Hope to submit by end of 2004

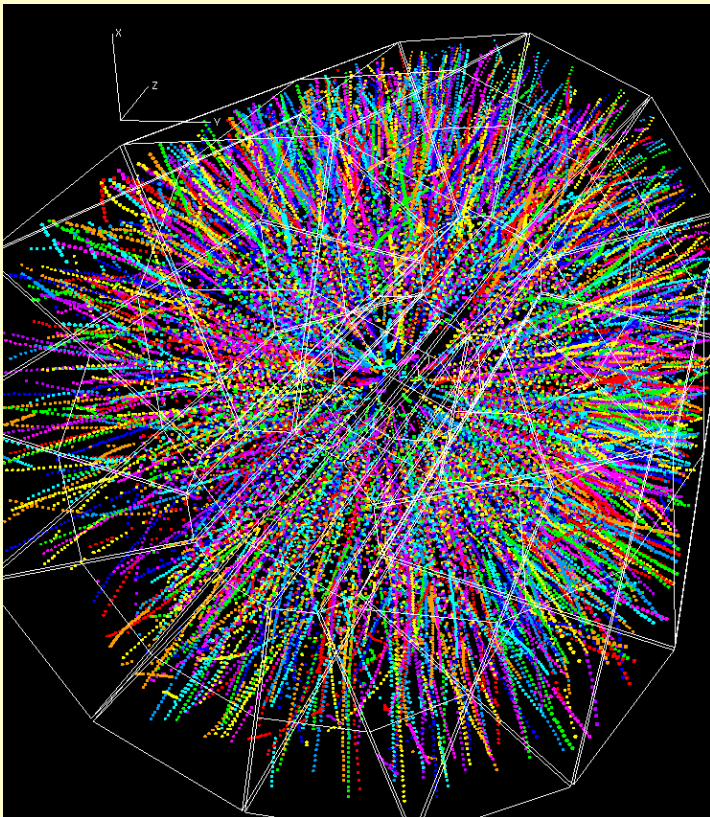


Tracking

Gaseous Tracking in the Third Millennium

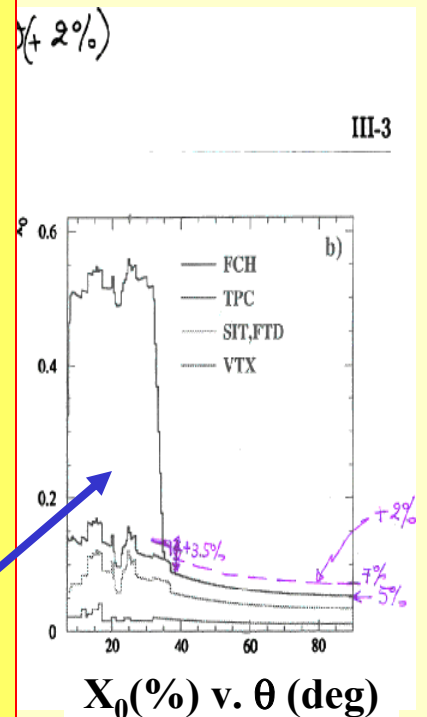
A TPC event from
STAR at RHIC

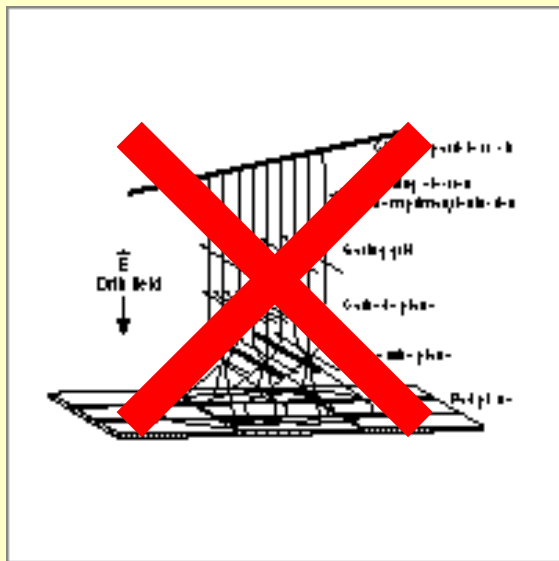
Tracking in heavy ion collisions is messy, but TPC's are highly pixellated



For the Linear Collider
Detector:

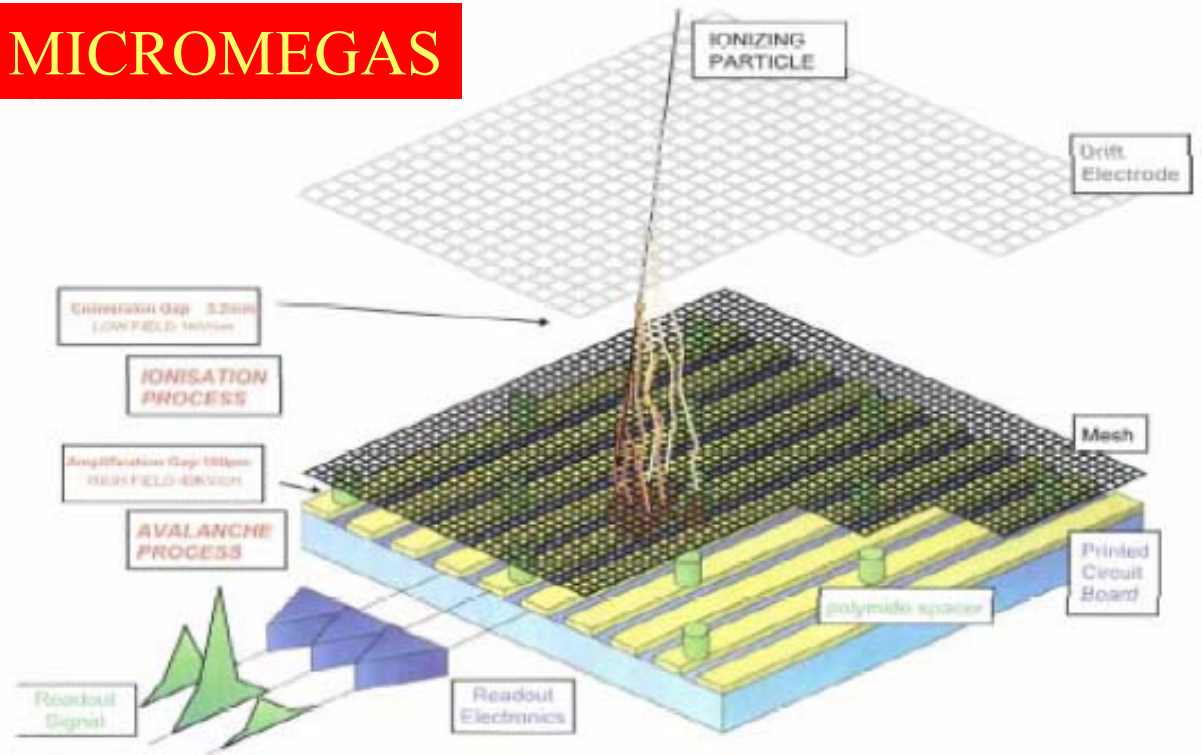
- Track *densities* are actually higher
- Baseline performance implies x3 improvement in point resolution
- Must avoid excessive material in endcaps (energy flow into forward calorimetry)





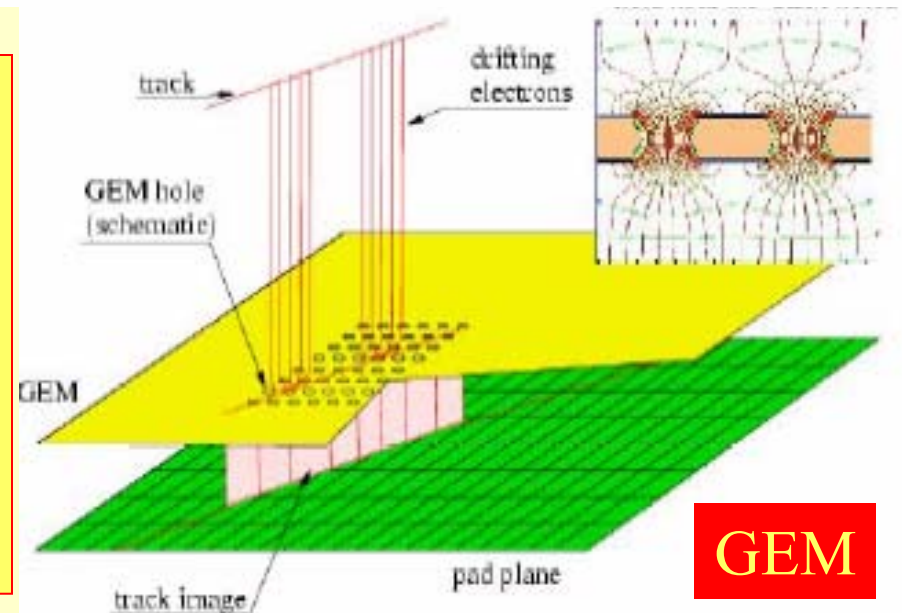
Traditional wire-plane readout too coarse

MICROME GAS



Micro-Patterned Gas Detectors

- Finer segmentation → better resolution
- Ion feedback into tracking volume is small if gain is kept low ($\sim 10^2$ per layer)



TPC Electronics Issues

Low Noise: want to keep gain low to avoid excessive feedback of ions into the drift volume

Channel Count: 2mm^2 pads (to achieve $100\text{ }\mu\text{m}$ resolution) implies $> 10^6$ channels; if limited ($350\text{ }\mu\text{m}$) transverse diffusion is exploited, would reach 10^8

Flash ADC: Exploiting longitudinal diffusion (z drift) resolution limit implies $\sim 100\text{ MHz}$ sampling

Signal Processing: Zero suppression, buffering, waveform processing, power cycling, etc. to keep electronics compact and material down

Begin upgrade of STAR/ALICE FEL or...

Readout of a TPC using the Medipix2 CMOS pixel sensor

(detection of single electrons on a
direct pixel segmented anode)

NIKHEF:

Alessandro Fornaini

Harry van der Graaf

Jan Timmermans

Jan Visschers

Peter Kluit

Saclay

Paul Colas

(CEA/DAPNIA)

Ioannis Giomataris

Arnaud Giganon

Univ. Twente/Mesa+:

Jurriaan Schmitz

CERN/Medipix Collaboration:

Erik Heijne

Thanks to: **Wim Gotink**

Joop Rovenkamp

Max Chefdeville

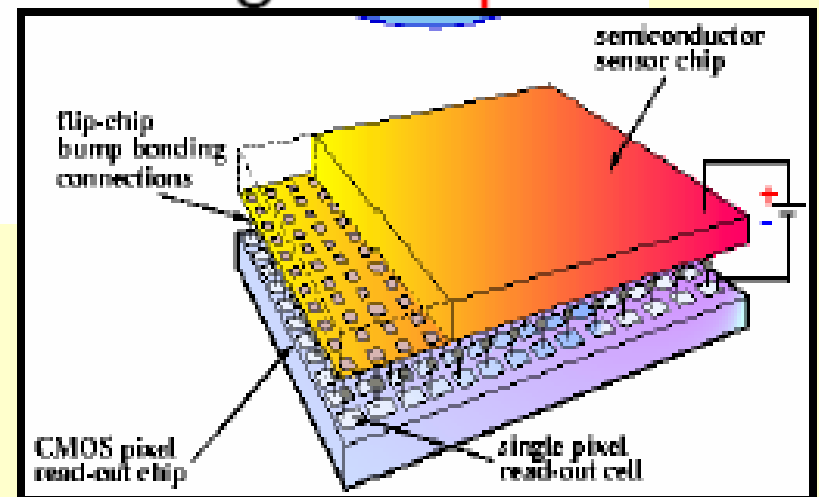
Goals

- **Gas multiplication** GEM or Micromegas foil(s)
- Charge collection with **granularity matching primary ionisation cluster spread**
- Needs **sufficiently low diffusion gas**
- dE/dx using **cluster counting?**
(→ M. Hauschild)
- Proof of principle based on existing **Medipix2** readout chip

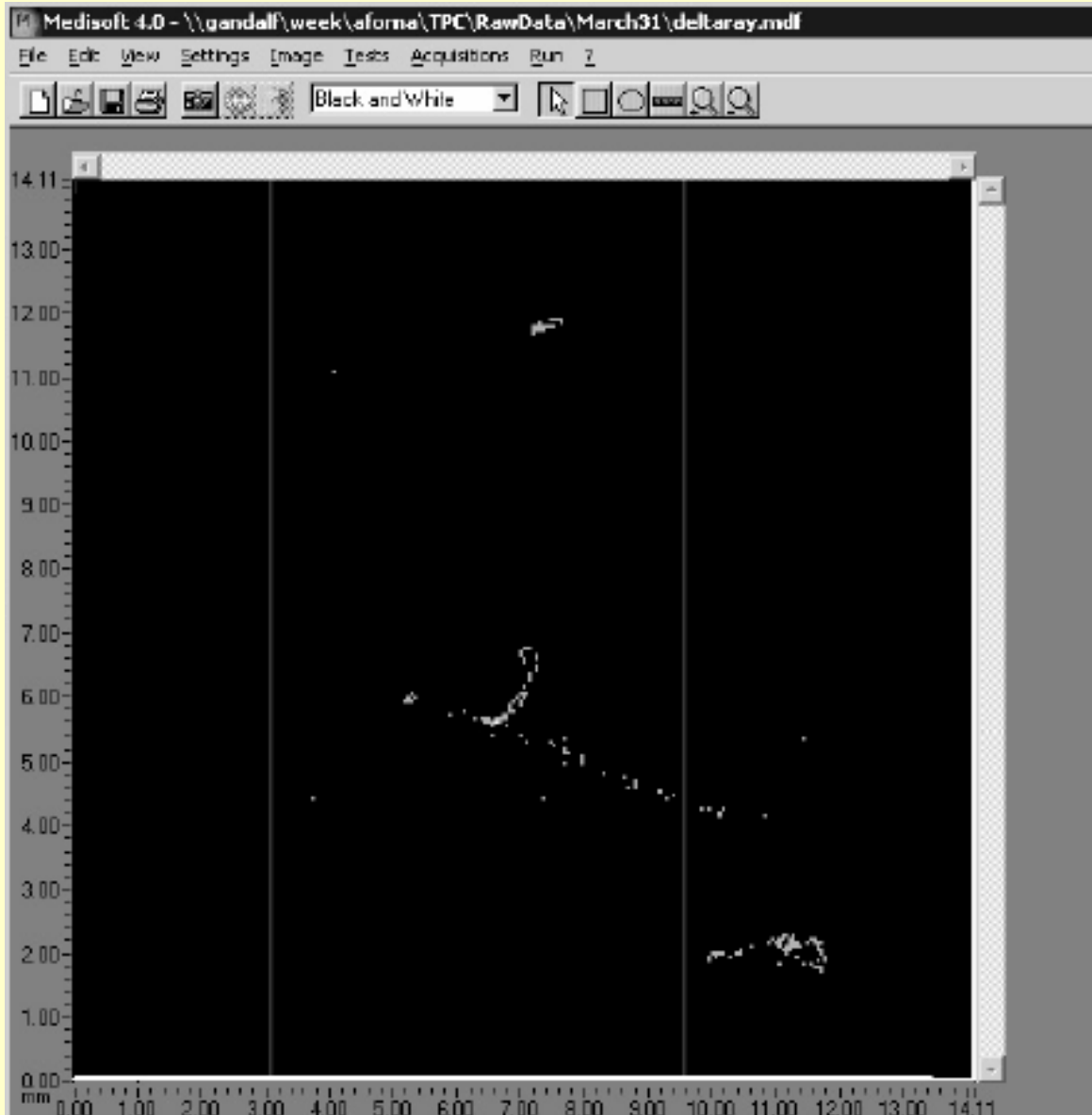
21 April 2004

LCWS 2004 Paris

Jan Timmermans, Nikhef



Jan Timmermans, Nikhef



Readout microMegas
detector with 55×55
 μm^2 pixel MediPix
chip

Clear depiction of
ionization path, δ -ray

Optimal for pattern
recognition, two-track
separation, dE/dX

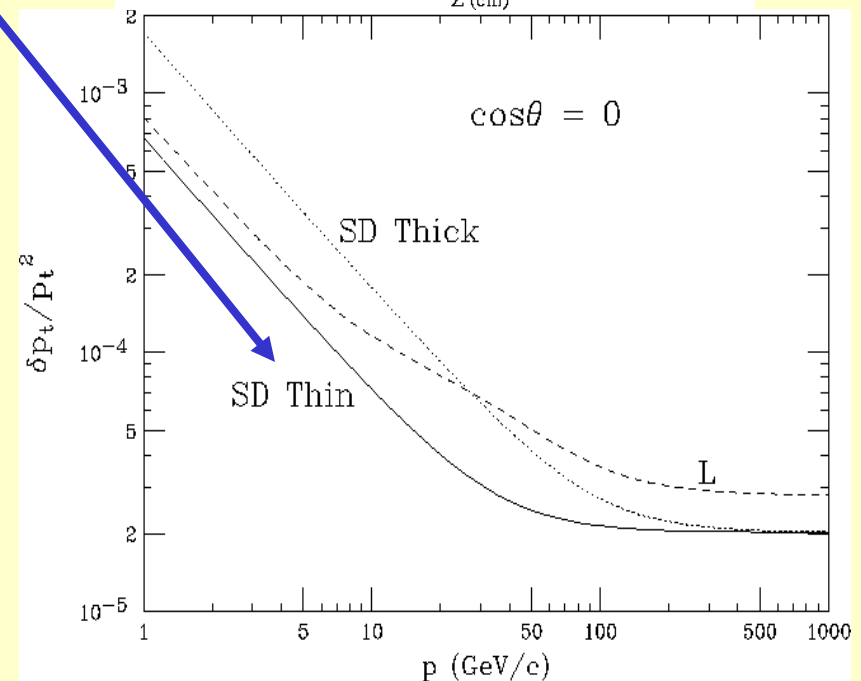
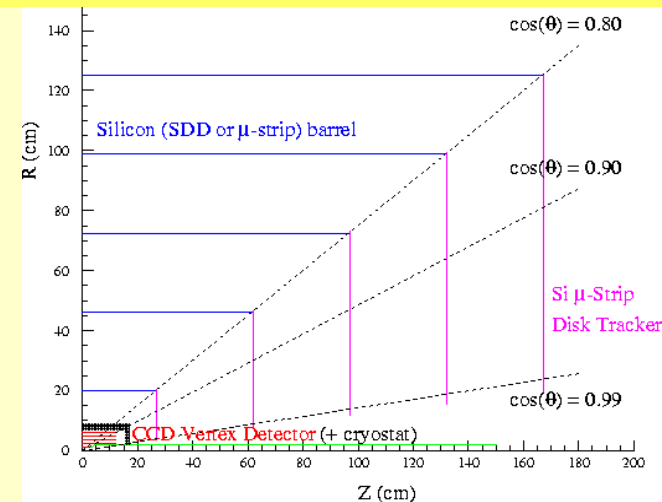
But: Approaches 10^{10}
channels!!

Solid-State Tracking: the 'Gossamer Tracker' Concept

What if the *only* material in the tracker was the minimum necessary thickness of Si?

- No support structure
- No cooling
- No electronics and servicing
- Thinner detectors towards lower radius

No – pigs can't fly. But...

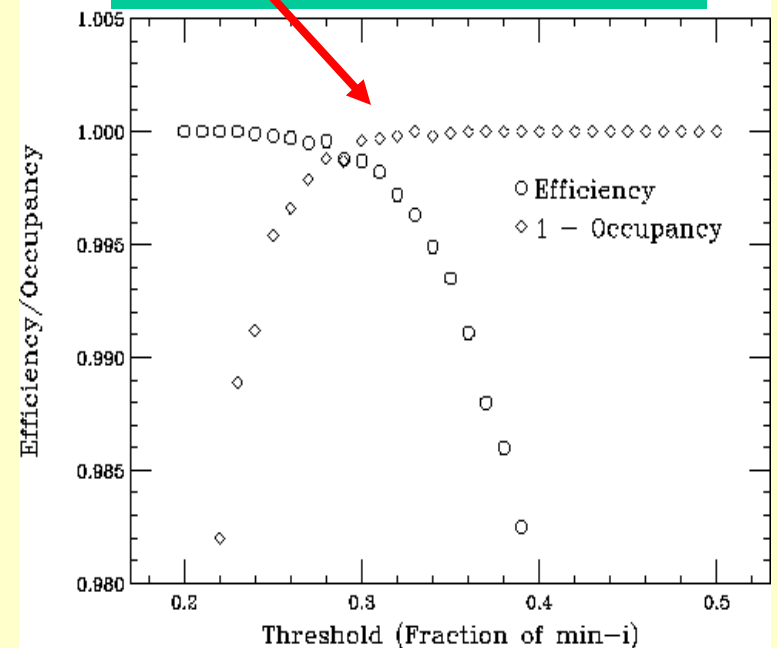


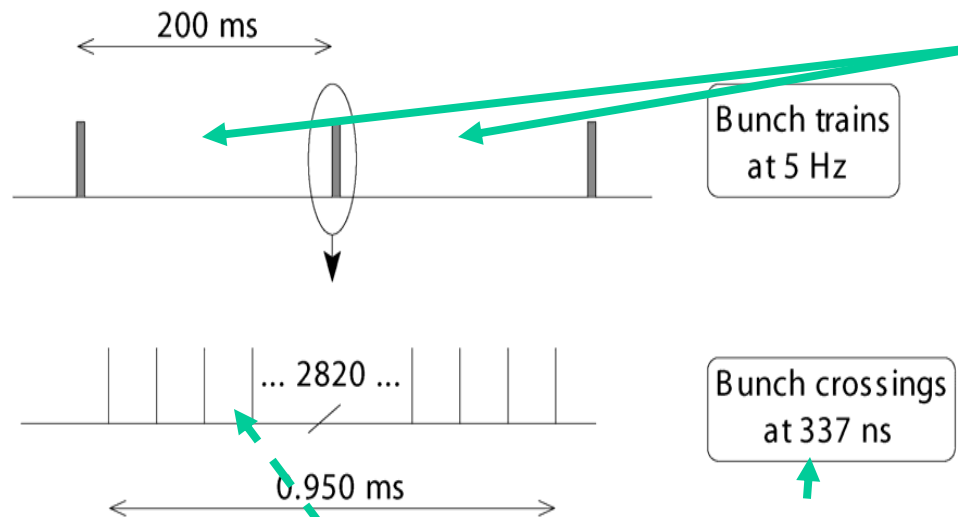
Shaping (μs)	Length (cm)	Noise (e^-)
1	100	2200
1	200	3950
3	100	1250
3	200	2200
10	100	1000
10	200	1850

Minimum-ionizing
for 300 μm of
silicon is about
24,000 electrons

Operating point
for 167 cm ladder

Simulations suggest that 3 μs
shaping time allows ladders
to be read from end only
→ no electronics servicing.





'Just' switch electronics off during these dead periods

→ ~99% power savings; eliminates need for active cooling

What about event pile-up in the tracker?

$$\sigma_t \cong \frac{\tau}{SNR}$$

Where SNR = signal-to-noise ratio. For $\tau = 3 \mu\text{s}$ and SNR = 12,

$$\sigma_t \cong 250 \text{ nsec}$$

Gossamer Tracker FEL Characteristics

Need to develop a chip that...

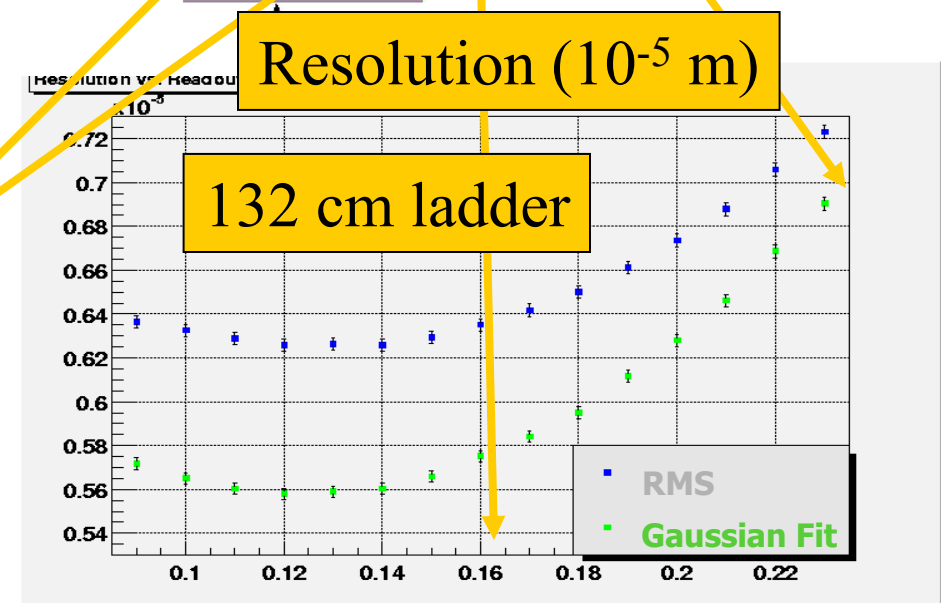
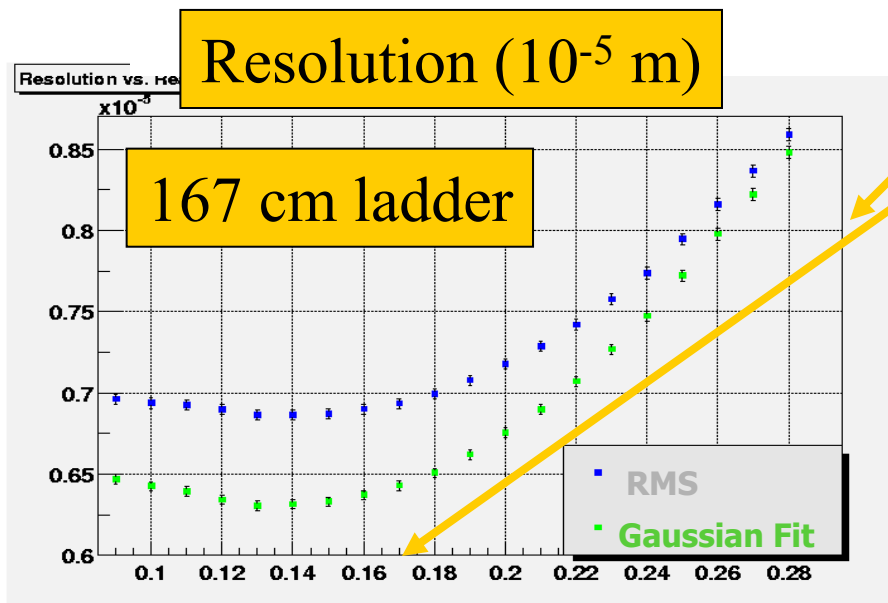
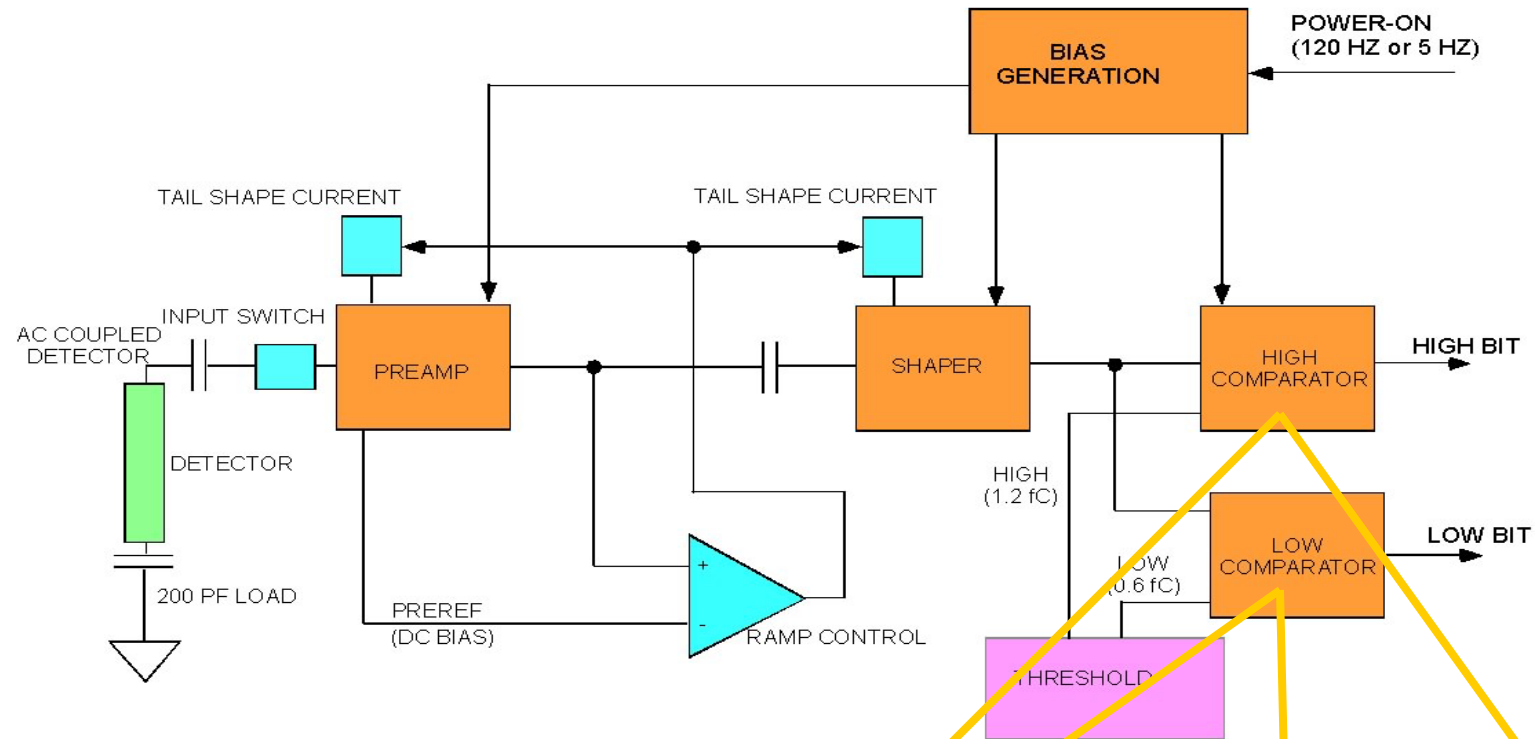
- Has low intrinsic noise
- Has long (several μs) shaping
- Can switch power on/off in $\sim 100 \mu\text{s}$
- Analog readout (centroid, dE/dX)
- Time stamping and pipeline

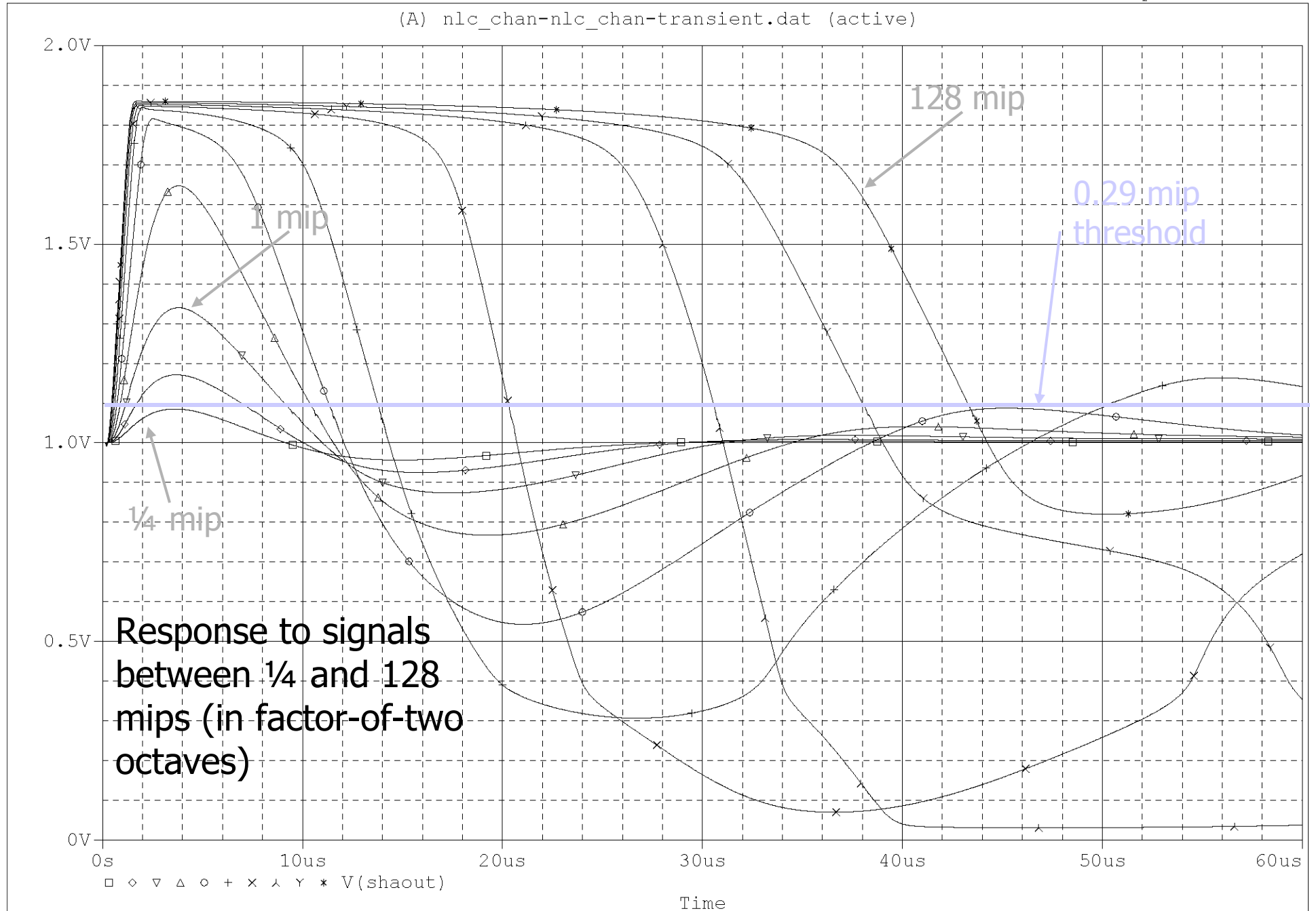
Complementary efforts at:

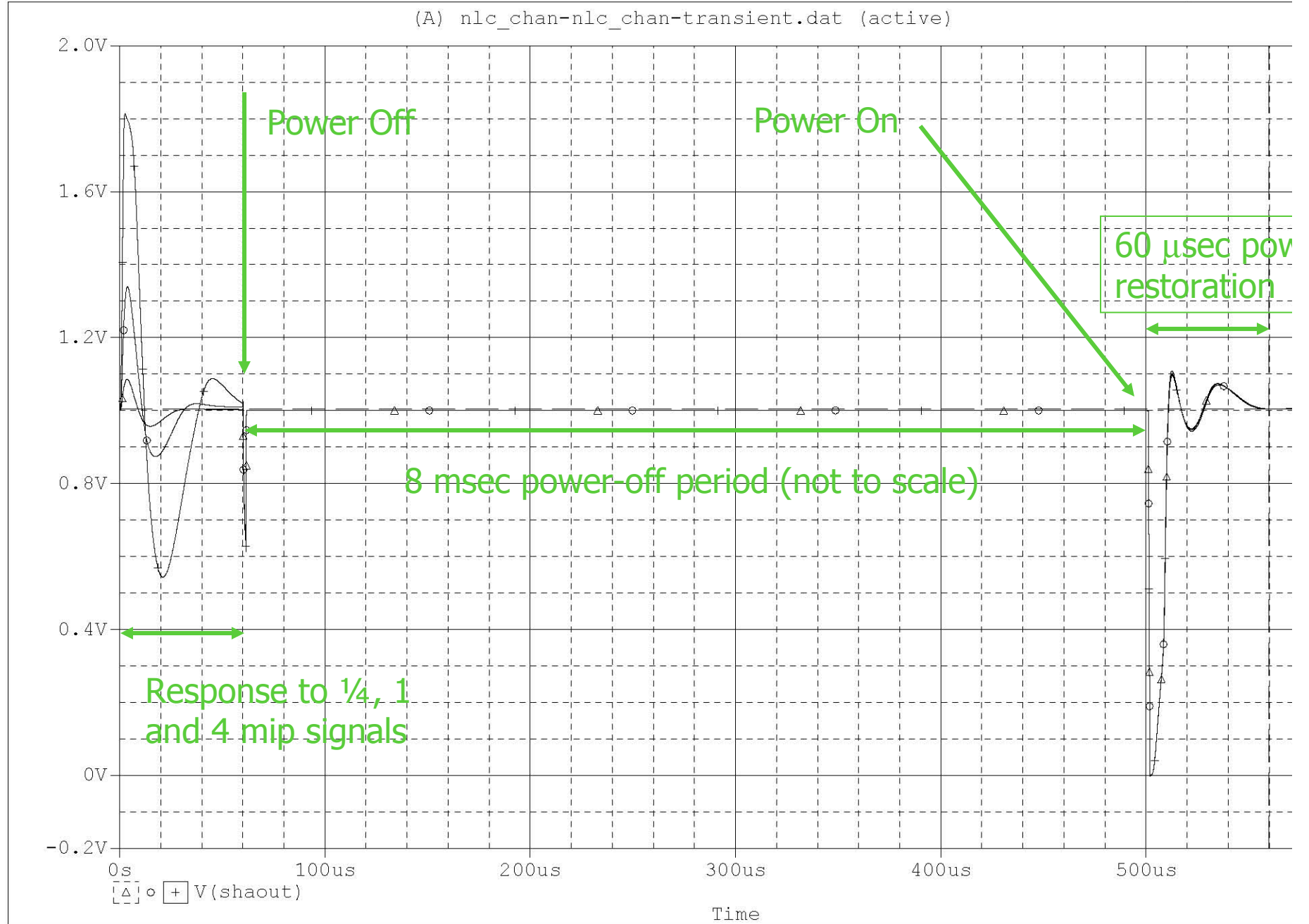
- LPNHE Paris
- UCSC (SCIPP)

Both targeting fall prototype run for example...

SILICON TRACKER FRONT-END ARCHITECTURE





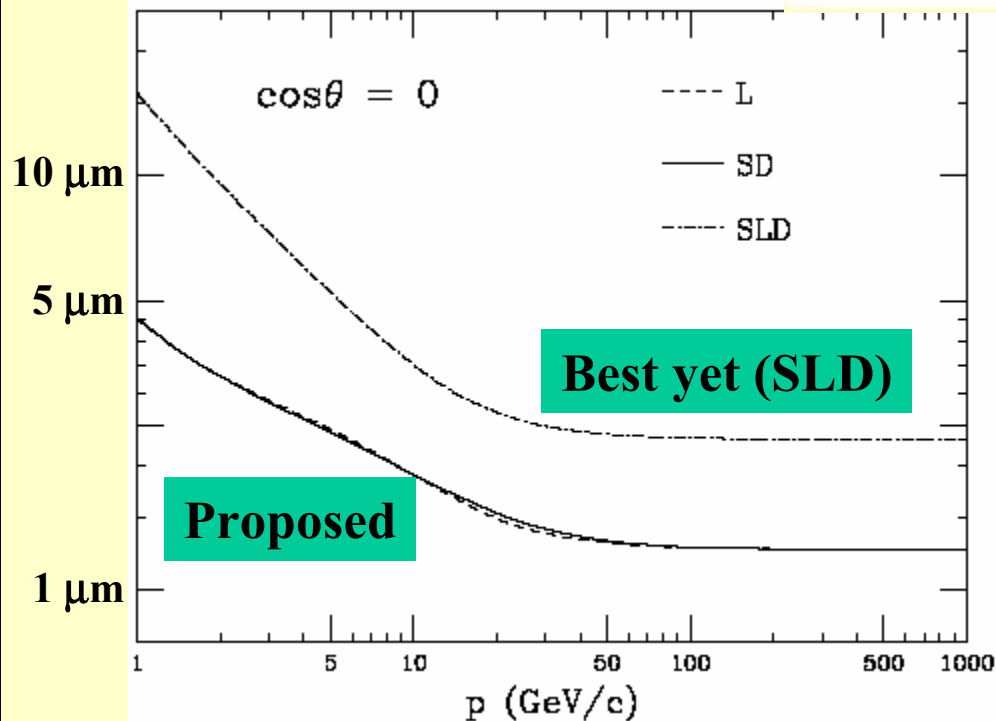
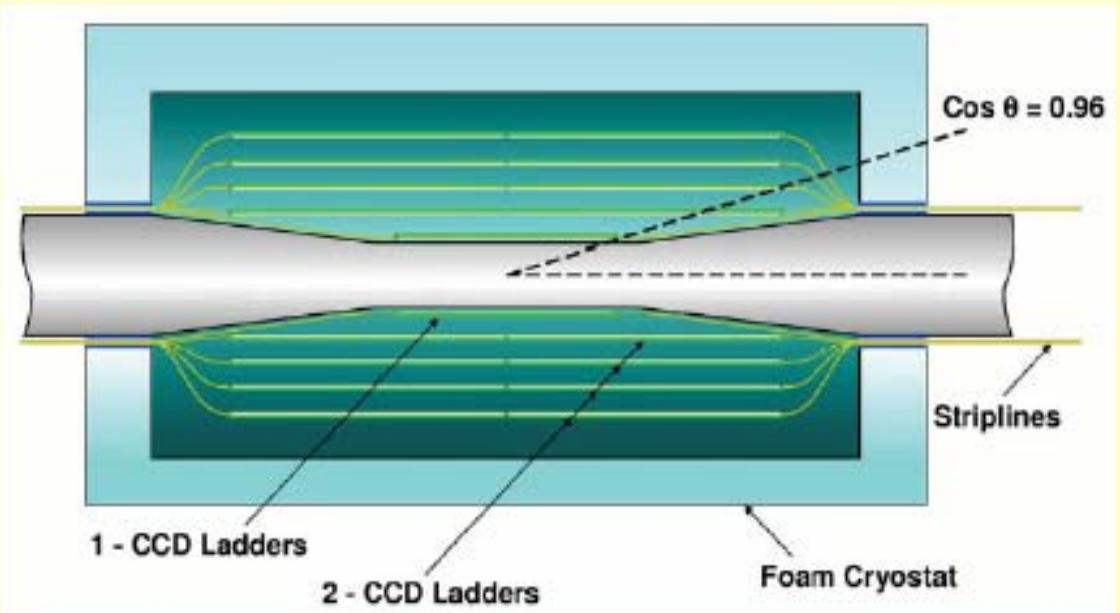


A1: (0.000, 1.0002) A2: (559.875u, 1.0038) DIFF(A): (-559.875u, -3.6378m)



Vertexing

Global Baseline LC Vertex Detector



Optimistic projections
achieved by very small
($\sim 20\mu\text{m} \times 20\mu\text{m}$) pixels
and very thin ($< 0.1\% X_0$)
layers

→ Thinned CCD's

But: transition from SLC to LC application is not immediate...

Typical CCD sensor includes roughly $\frac{1}{4}$ million pixels and takes $\sim 100\text{msec}$ to read out with a 5 MHz clock

For the LC, this would integrate over the full train of 2,820 pulses, leading to intractable backgrounds

→ Speed up and de-serialize readout

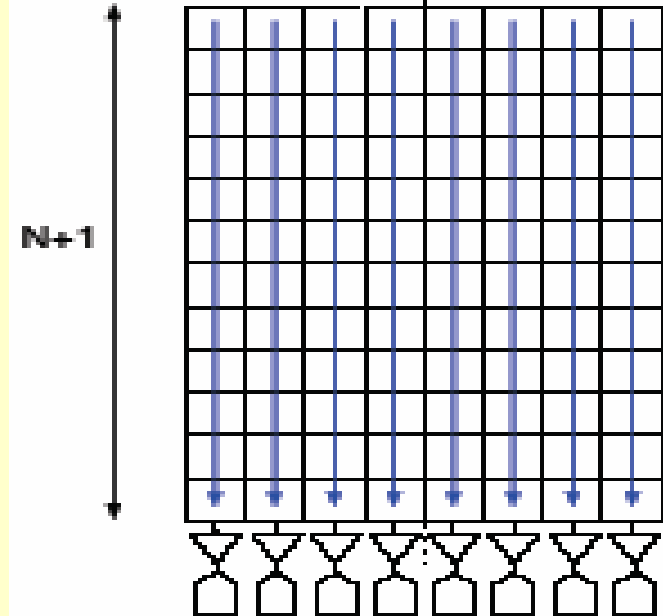
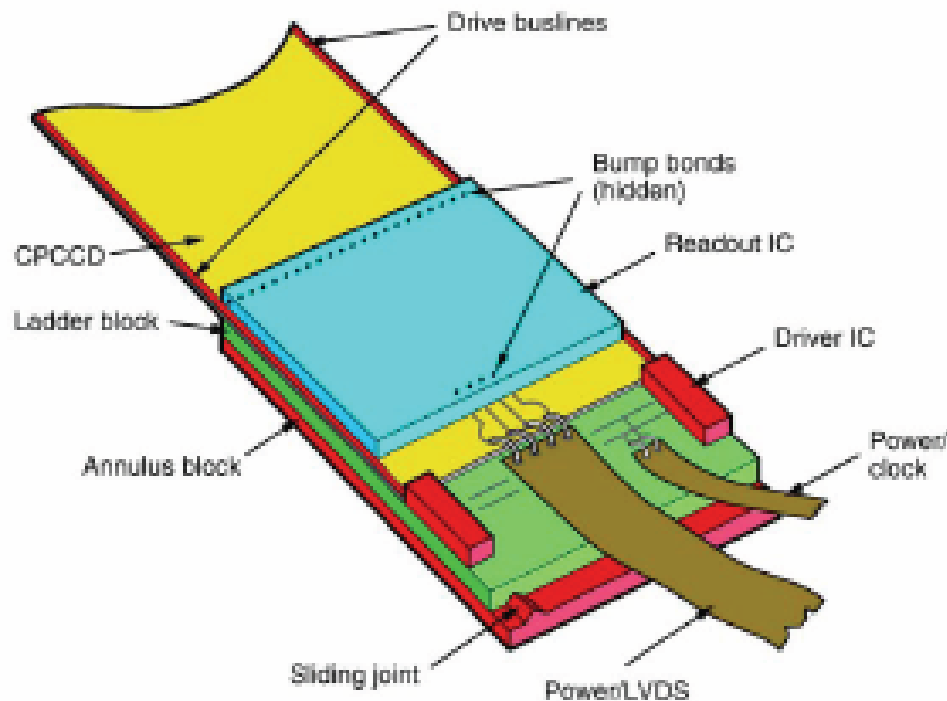
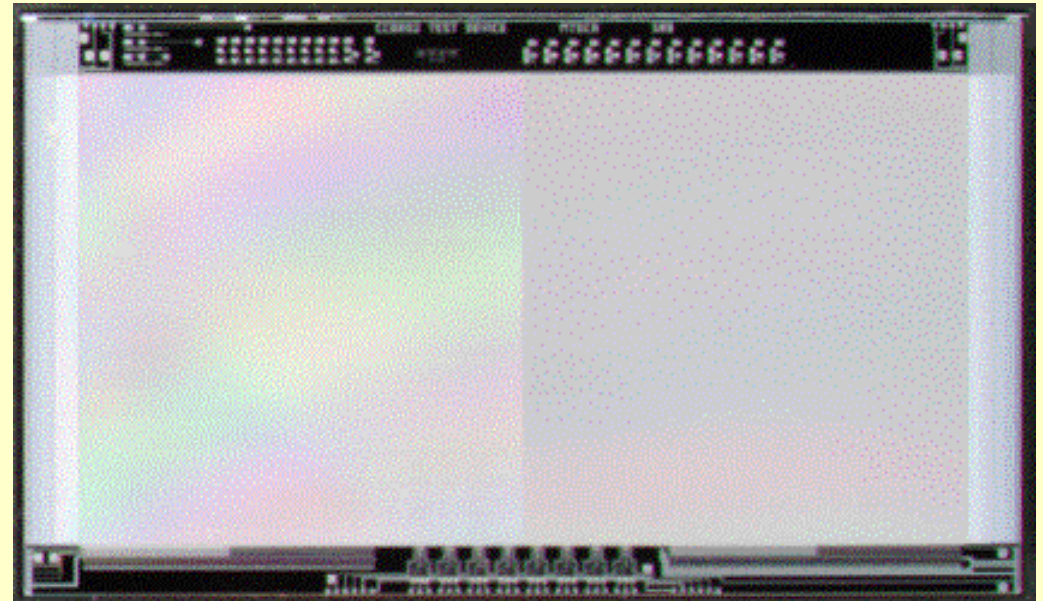
Column-parallel CCD readout architecture



Our first CPCCD

Column-parallel CCD has
been developed (E2V
corporation)

Readout scenarios under
development



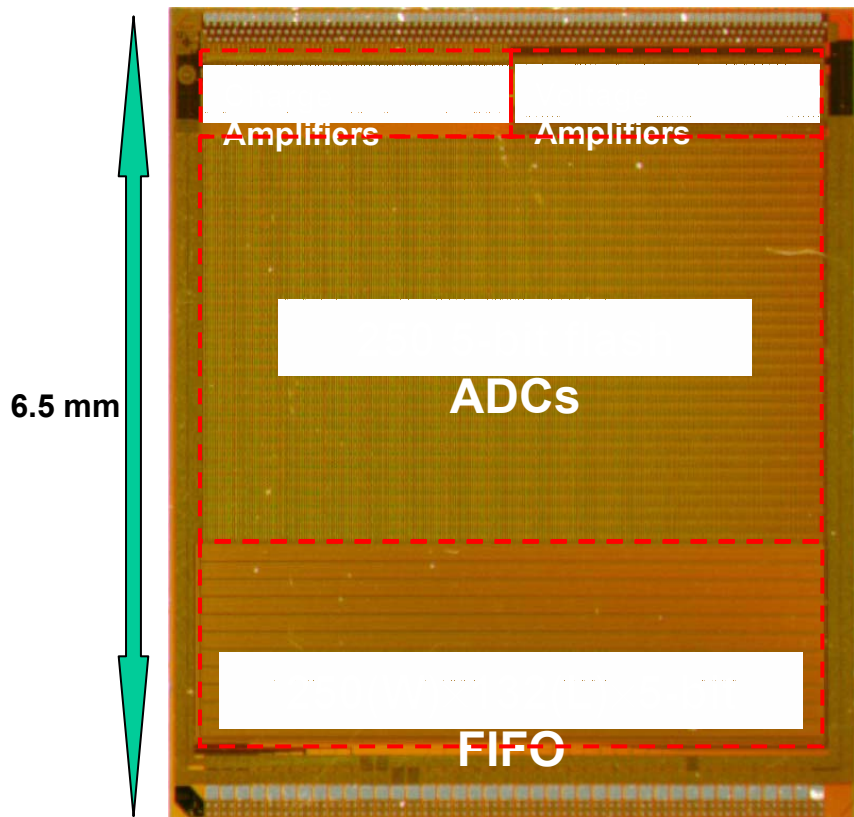
Column Parallel CCD
Readout time = $(N+1)/F_{out}$



Readout Chip CPR1

6 mm

Wire/bump bond pads



6.5 mm

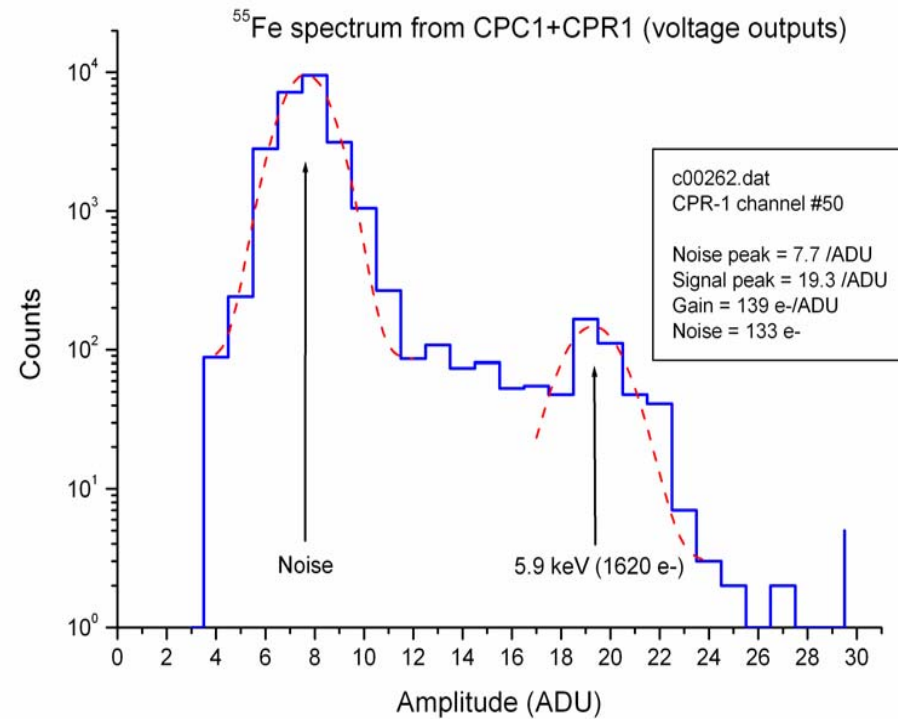
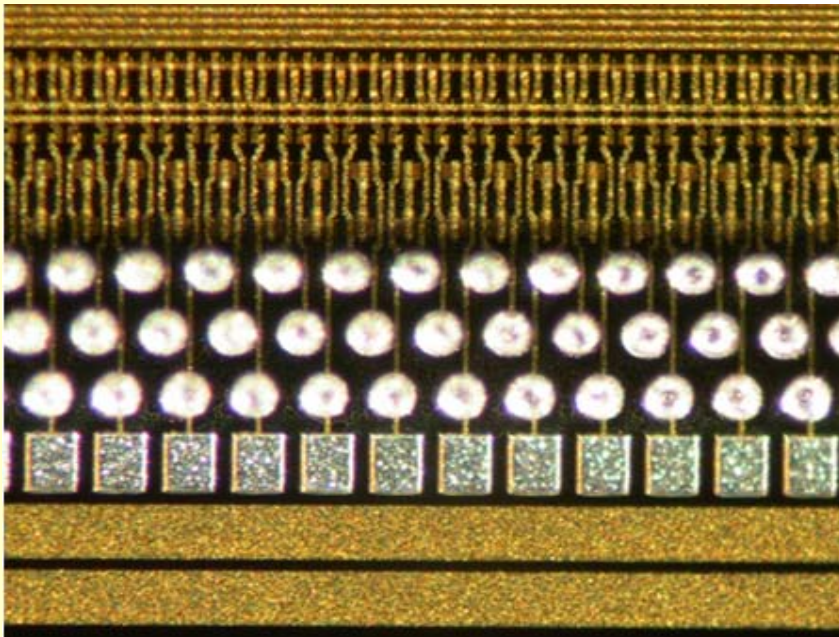
Wire/bump bond
pads

ASIC for CPC-1 readout

- design: RAL Microelectronics Group
- **voltage amplifiers** for 1-stage SF outputs
- **charge amplifiers** for direct outputs
- 20 μm pitch, 0.25 μm CMOS process
- wire- and bump-bondable
- **scalable and designed to work at 50 MHz**

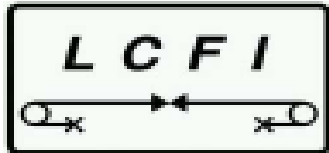


- bump bonding performed by VTT (Finland)
- connecting to CCD channels at effective pitch of $20\mu\text{m}$ possible by staggering of solder bumps



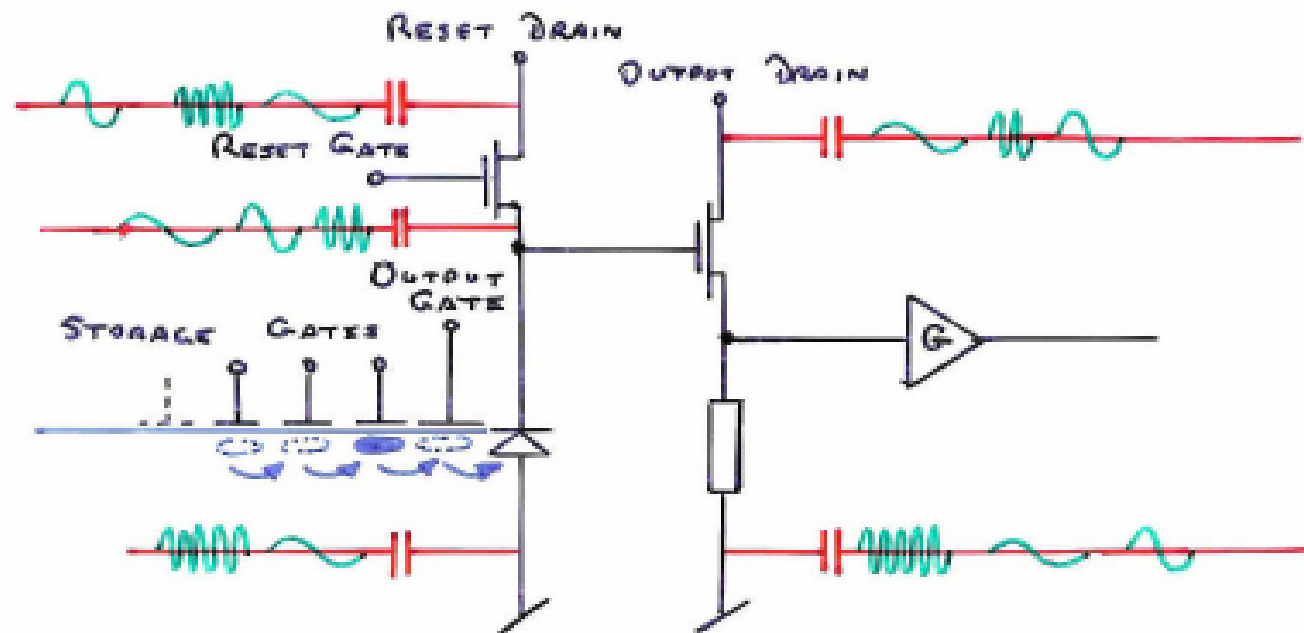
Spectrum (^{55}Fe) observed from voltage output (less aggressive) nodes; beginning to look promising

BUT: in order to avoid event pile-up, you must read out the detector (many times over!) during the spill...



Chris Damerell, Rutherford Labs (LCWS04)

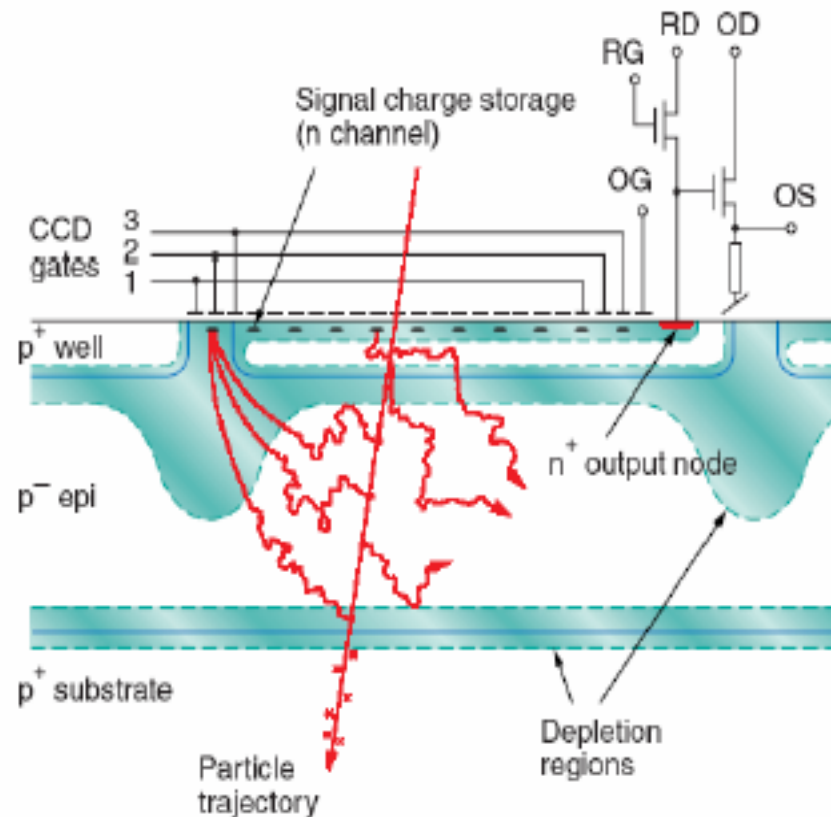
Readout at Linear Collider during bunch train:



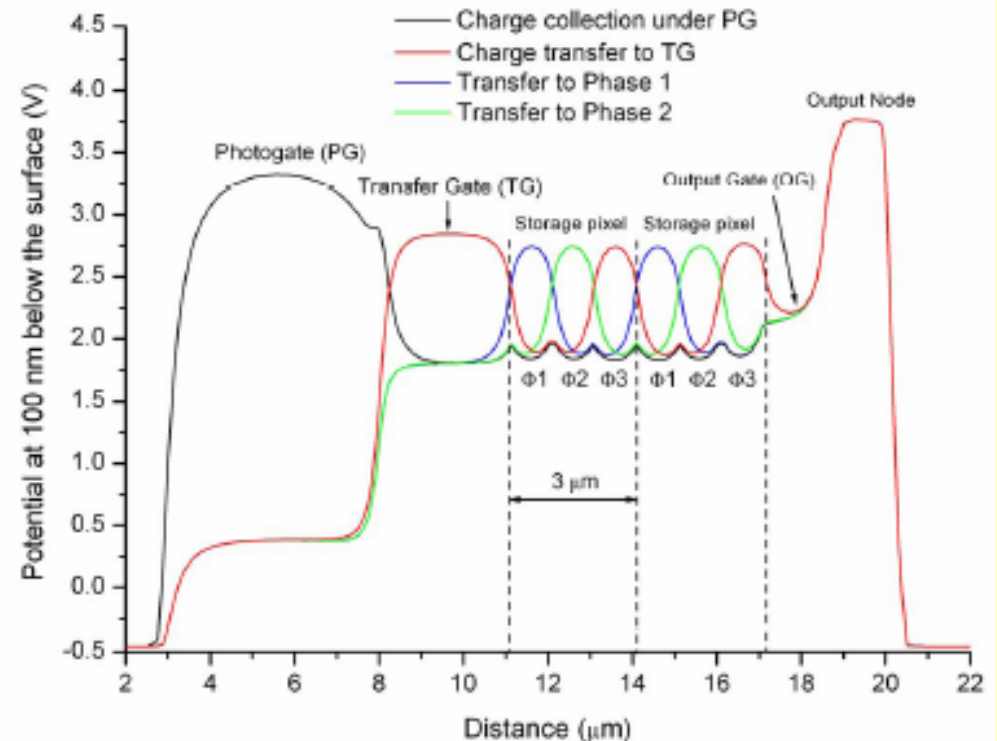
Malos's first rule of electronics: 'There is no such thing as ground ...

Why *whisper* just when an express train roars through the station?

In-situ storage of signal charge: a new architecture for TESLA



Store charge in 20 slices
during $\sim 1\mu\text{sec}$ spill; read out
between spills



But is there a Plan B??!!

Progress in Active Pixel R&D

'Monolithic' designs (electronics deposited directly onto sensors) – why?

Typical current active pixel detector:

- Large-pitch pixel sensor ($\sim 100\text{ }\mu\text{m}$ or more)
 - Readout circuitry with fill-factor ~ 1
 - Bump bonds
 - Servicing and cooling
- ➔ Does not achieve ideal impact parameter resolution due to pitch and material burden

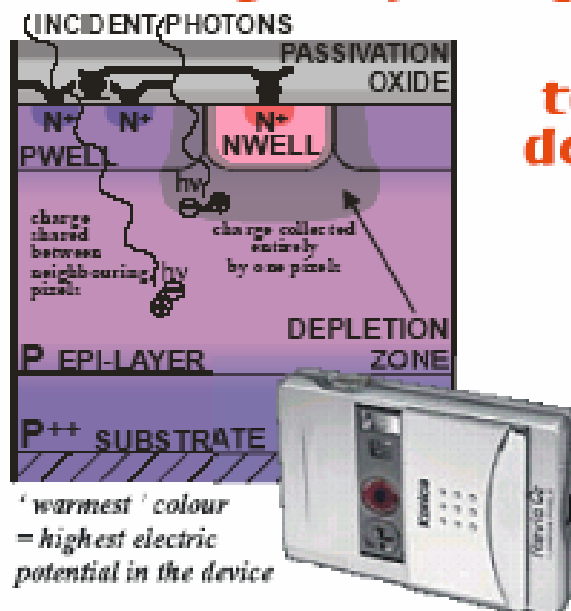
A number of different approaches are being explored...

- MAPS (Monolithic Active Pixel Sensor)
- FAPS (Flexible Active Pixel Sensor)
- DEPFET (Depleted Field Effect Transistor) APS
- SOI (Silicon on Insulator) APS

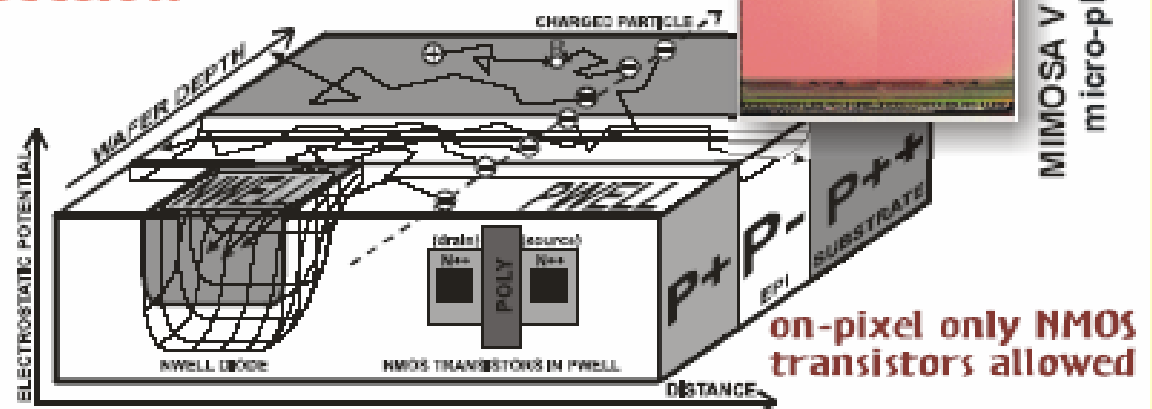
Active Pixel Sensors (APS)

Existing application in high-end digital photography; development for particle physics detection led by **LEPSI** electronics consortium at **IRES Strasbourg**.

From digital photography



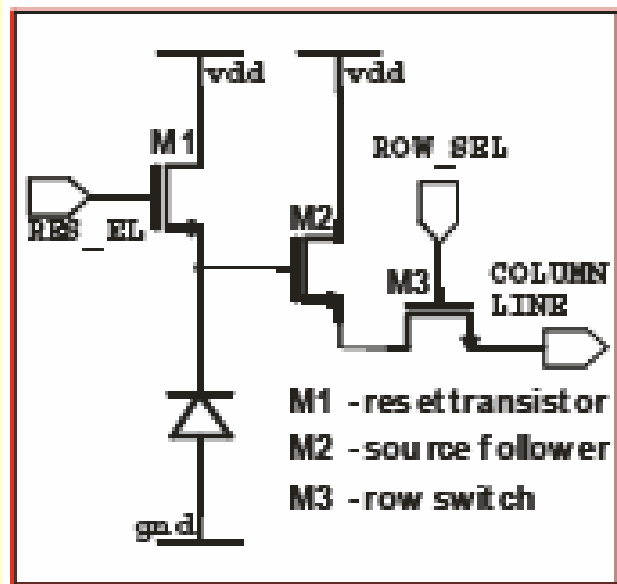
to charged particle
detection



Monolithic Active Pixel Sensors (MAPS)

Basic idea: readout grown directly onto epitaxial layer of VLSI sensor; charge collected via diffusion through epilayer

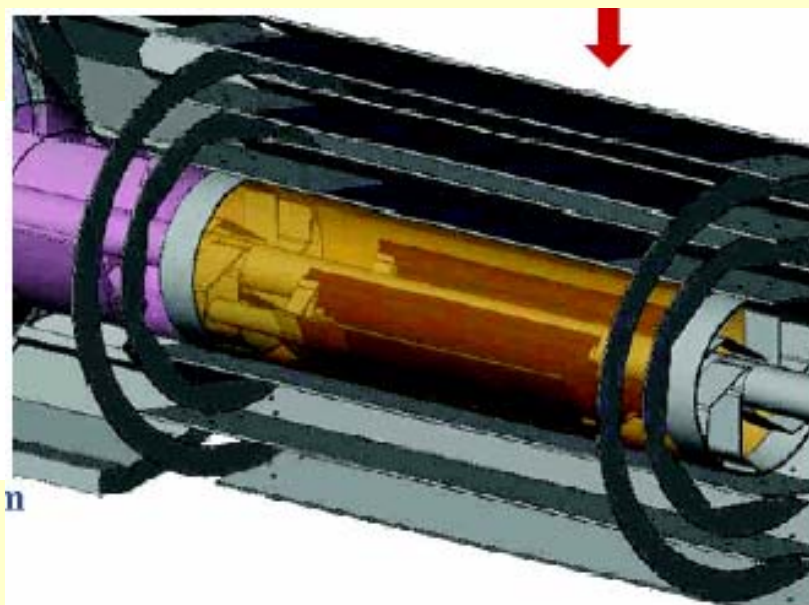
MIMOSA V: Proof of Principle



RESULTS:

Noise mean ENC:	20.74 e^-
Single pixel S/N mean:	22.73
detection efficiency e^- :	99.3%
spatial resolution s :	1.7 μm
pixel-pixel gain nonuniformity	~3%
macro-scale gain nonuniformity:	~0.2%

Now under development:
'MIMOSA STAR' for
use in STAR vertexing
layers



Similar to CCD's, must go to faster, parallelized readout for Linear Collider → increased on-pixel functionality

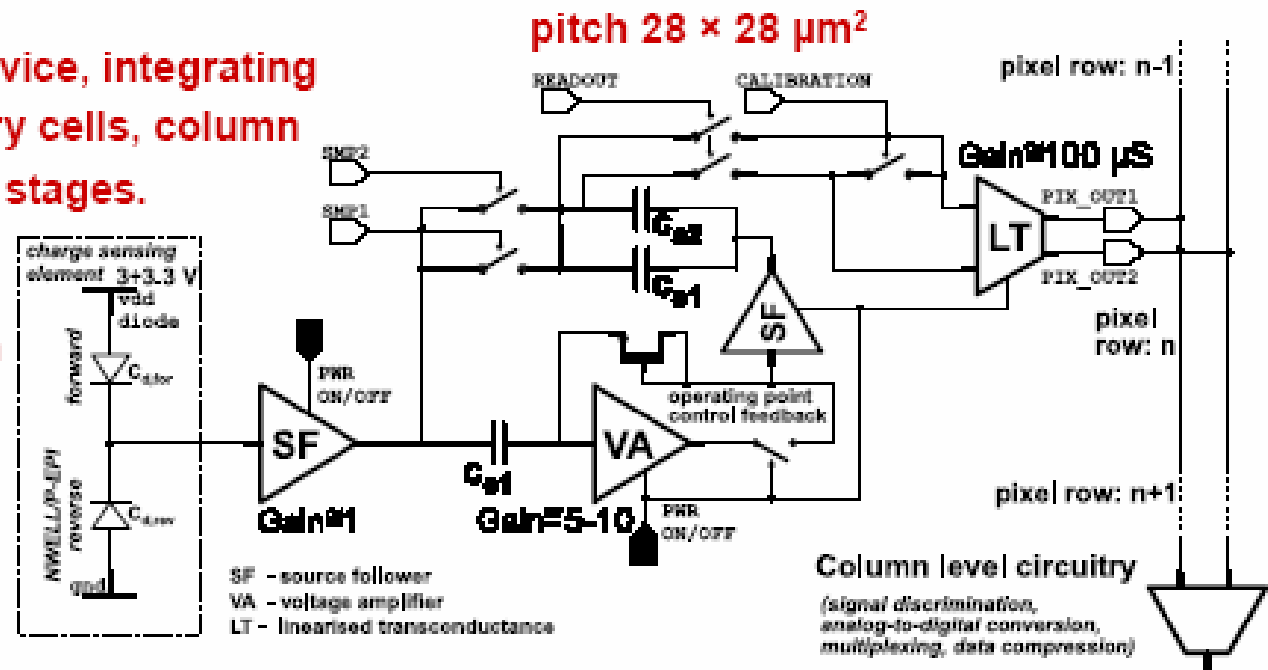
- Sample-and-hold (switched capacitors)
- Zero suppression
- Addressable for column-parallel readout

►► MIMOSA VI

►► MIMOSA VI - first tested device, integrating on-pixel voltage mode memory cells, column || readout, and discrimination stages.

►► main features:

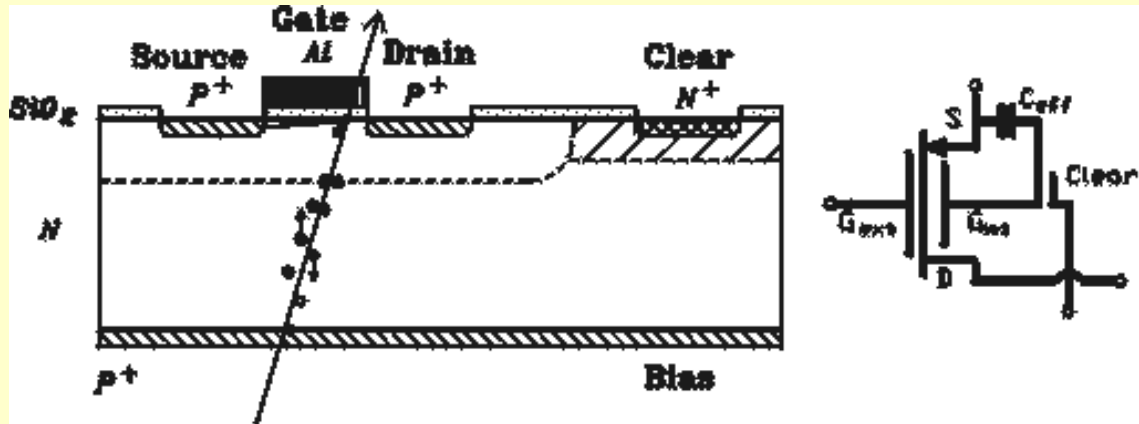
- mixed 0.35 μm process with 4 μm epitaxial layer,
- array of 128 rows \times 30 columns read in || with CDS + signal discrimination (total 25 μs)
- AC coupled on-pixel voltage amplifier + CDS,



But deep submicron processes still promise attractive pitch, and active portion of device is intrinsically thin.

DEPFET principle and properties

DEPFET structure and device symbol



Function principle

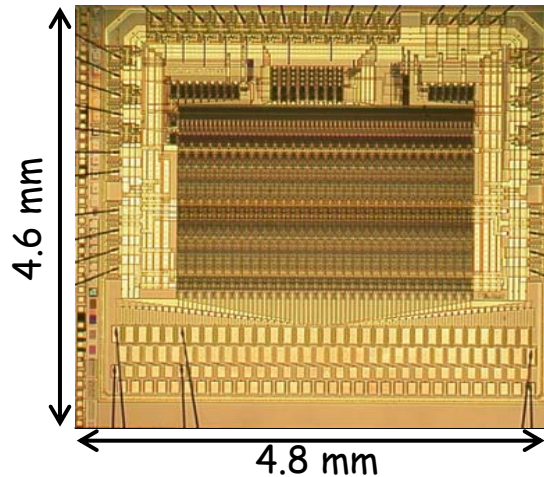
- Field effect transistor on top of fully depleted bulk
- All charge generated in fully depleted bulk; assembles underneath the transistor channel; steers the transistor current
- Clearing by positive pulse on clear electrode
- Combined function of sensor and amplifier

Participants: MPI Munich, MPI Halle, Mannheim, gGmbH Munich, Bonn; material presented here due to Gerhard Lutz, MPI Munich

DEPFET Matrix Read Out: ASICs

Development at the Universities Bonn and Mannheim

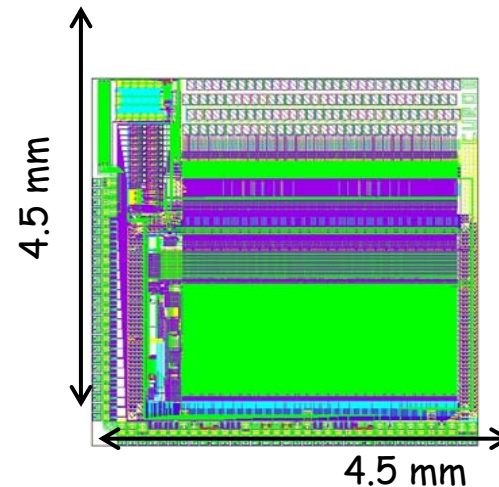
Switcher II:



Readout row selection chip

- AMS 0.8 μ m HV
- high speed
- high voltage range (20V)
- 64 rows=2x64 channels
- daisy chainable

CURO II:



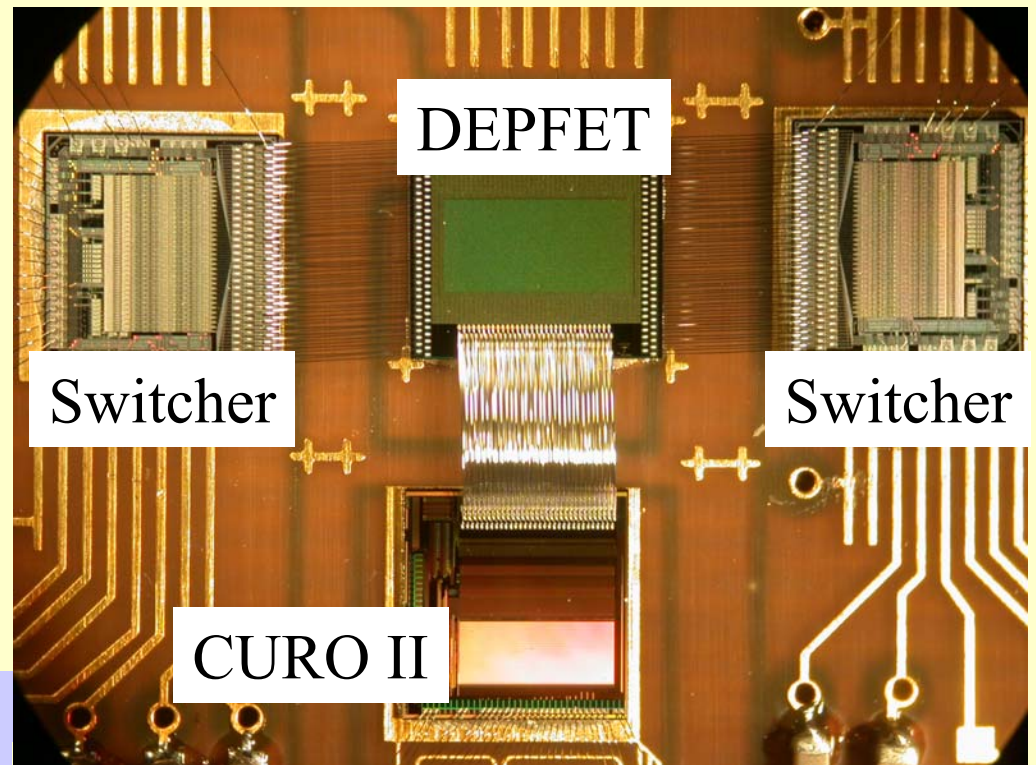
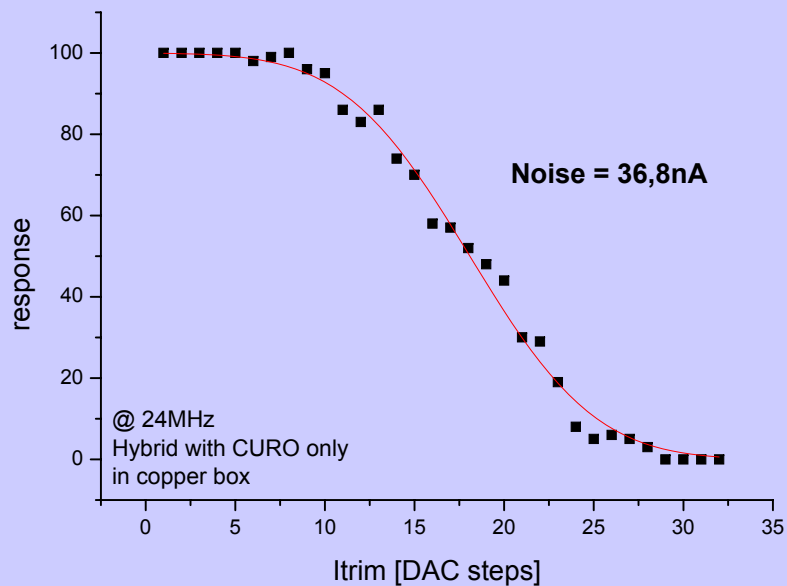
Fast RO chip for DEPFETs

- TSMC 0.25 μ m, 5 metal
- 128 channels „CUrrent ReaOut“
- fast current based memory cells
- hit identification + zero suppression
- Correlated double sampling within 40ns

DEPFET STATUS

Basic versions in use in
XRAY astrophysics, medical imaging.

noise performance via threshold scan:



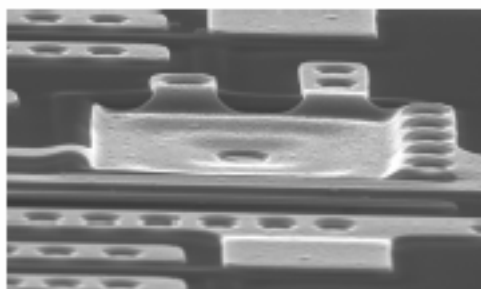
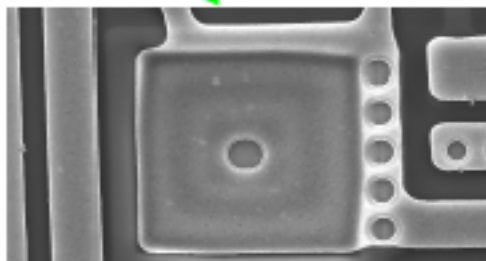
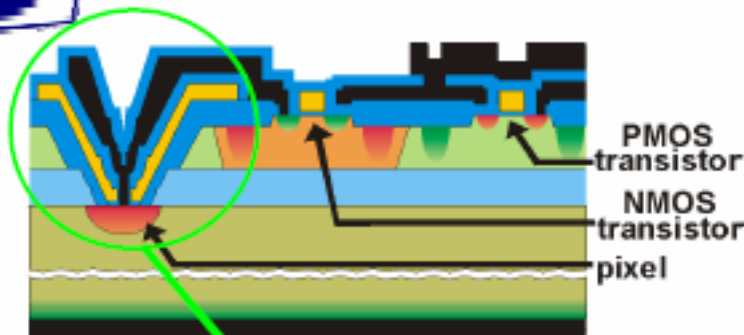
For LC: time structure,
precision demand faster
frame rate, power cycling;
prototype is really just
proof-of-principle at this
point.

Silicon on Insulator (SOI) Detector Concept

AGH Krakow, IET Warsaw, U. of Insubria (Como)



Principle of SOI monolithic detector



The idea:

Integration of the pixel detector and readout electronics in the wafer-bonded SOI substrate

Detector → handle wafer

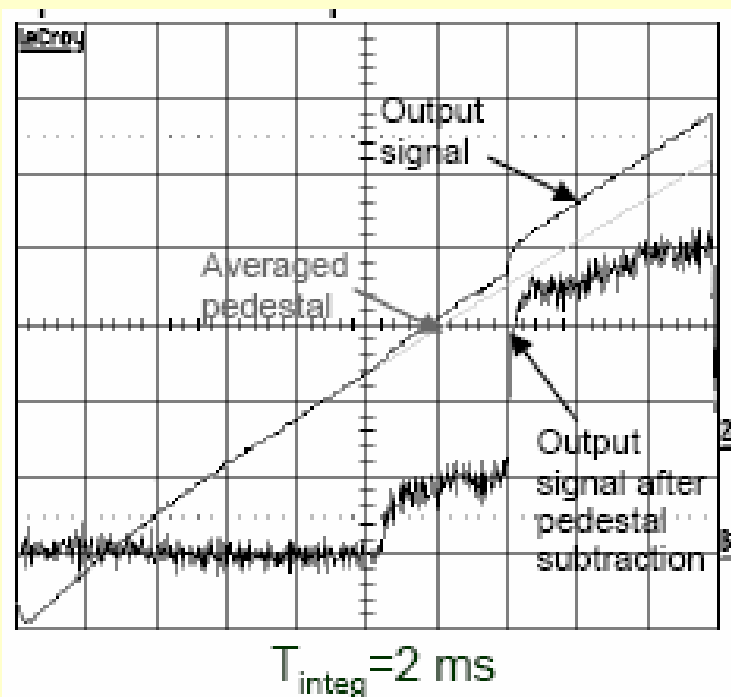
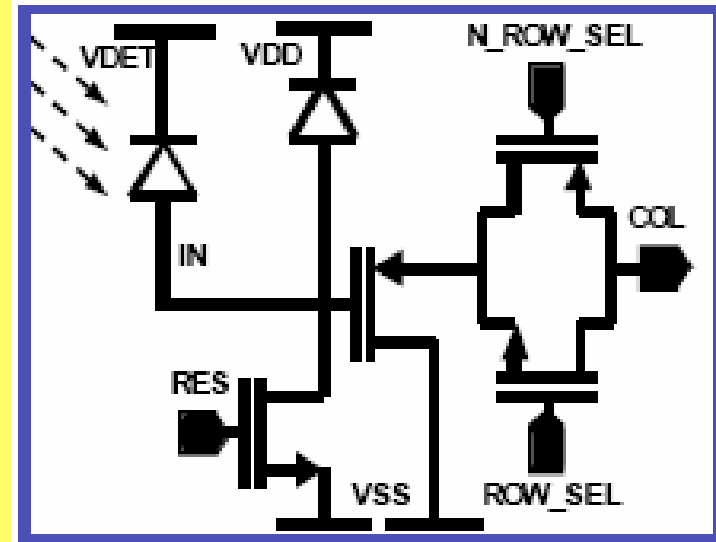
- High resistive ($> 4 \text{ k}\Omega\text{cm}$, FZ)
- $300 \text{ }\mu\text{m}$ thick
- Conventional p^+-n
- DC-coupled

Electronics → active layer

- Low resistive ($9\text{-}13 \text{ }\Omega\text{cm}$, CZ)
- $1.5 \text{ }\mu\text{m}$ thick
- Standard CMOS technology

Approach promises large signals
since substrate is depleted; can
use both NMOS and PMOS

Group has observed signals
(^{90}Sr β source) with correlated
sampling



But pixel size is large ($150 \times 150 \mu\text{m}^2$) and integration
time long

→ Substantial R&D needed
if technology is to be
attractive for LC detector

Summary

LC detector development leading to many interesting R&D threads (with some interdisciplinary applications)

Most initiatives unique to LC (precision, bunch structure, power cycling)

Boundaries between detector and front-end electronics becoming obscured in some cases

Timeline for baseline (500 GeV) LC is surprisingly short: we are in the midst of the R&D phase

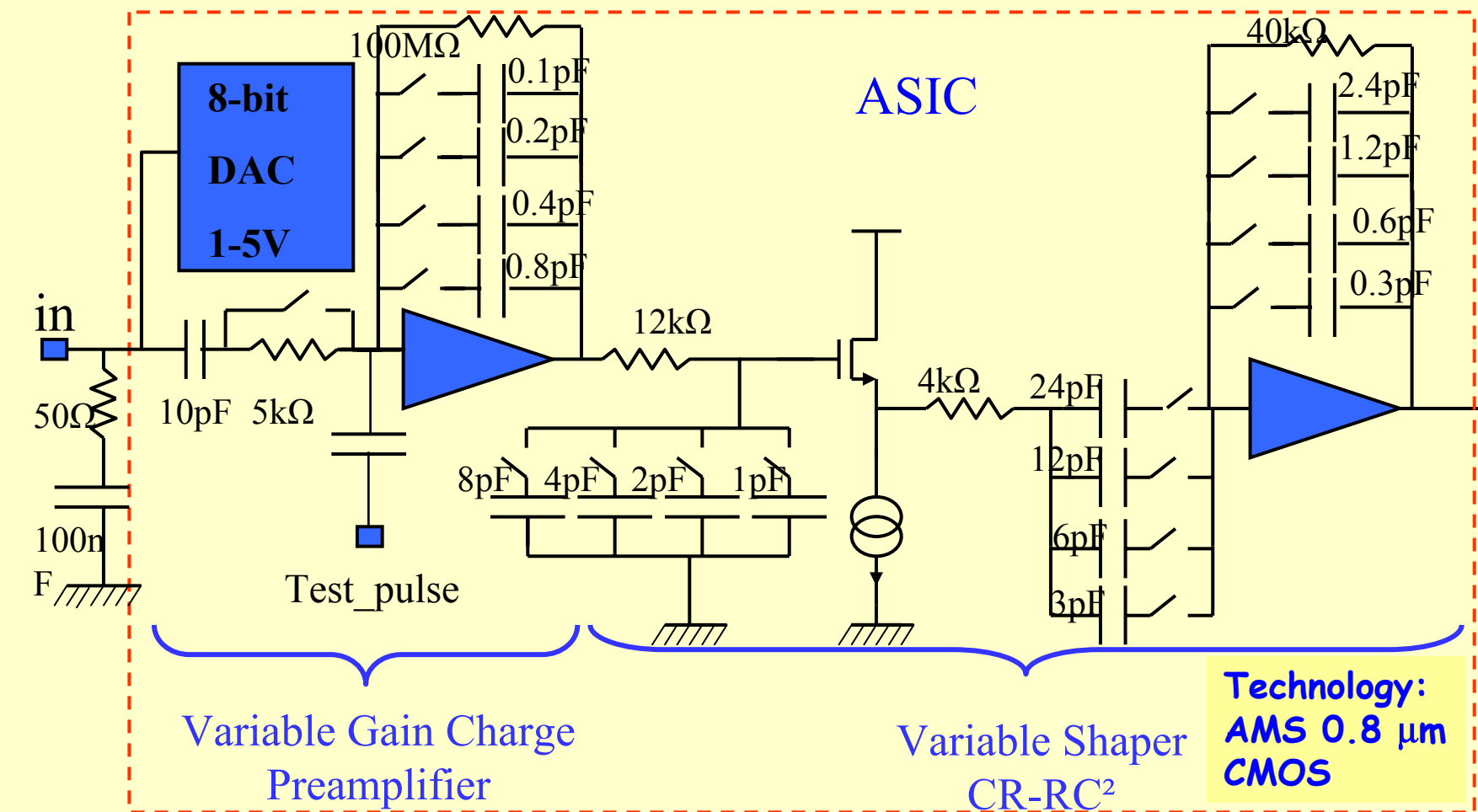
Next LC (machine) step: formation of International Design Group (IDG). Although far from certain, the LC is moving forward.

EXTRA SLIDES

Mimosa prototypes

CHIP	YEAR	PROCESS	EPITAXIAL	PITCH	METAL	PECULIAR
			μm	μm		
M1	1999	AMS 0.6 μm	14	20	3M	thick epitaxy
M2	2000	MIETEC 0.35 μm	4,2	20	5M	thin epitaxy
M3	2001	IBM 0.25 μm	2	8	3M	deep sub- μm
M4	2001	AMS 0.35 μm	0 !	20	3M	low dop. Substrate
SUC 2	2003	AMS 0.35 μm	none	40	3M	low dop. Substrate (SUCIMA project)
M5 & M5B	2001/2003	AMS 0.6 μm	14	17	3M	real scale 1M pixels
M6	2002	MIETEC 0.35 μm	4,2	28	5M	col. // r.o. and integrated spars.
M7	2003	AMS 0.35 μm	none	25	4M	col. // r.o. and integ. spars. (photoFET)
M8	2003	TSMC 0.25 μm	8	25	5M	col. // r.o. and integrated spars.
M9	2004	AMS 0.35 m	20	20/30/40	4M	opto. tests diodes/pitch/leakage current.
SUC 1						irradiation tests

Variable Shaping-Time / Variable Gain ASIC



From L.Raux

